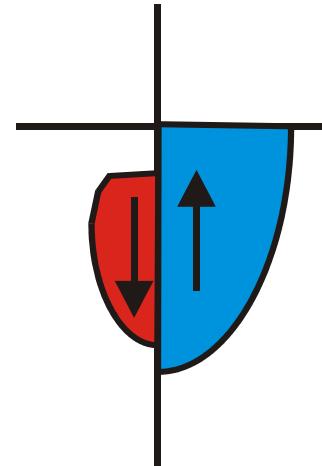


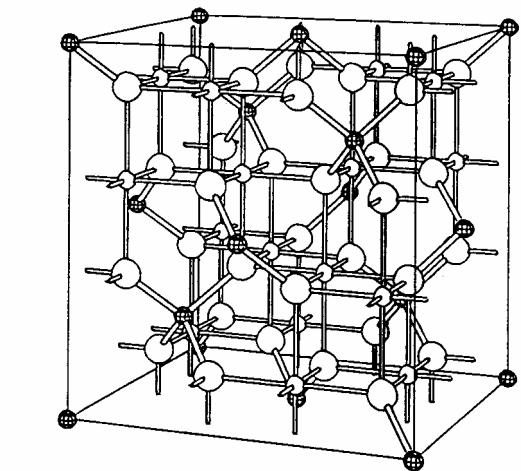
Half Metals



- One spin band present at E_f
- MTJs with $\frac{1}{2}$ -metals show large effects
 - 200% MR with I electrode
 - M-I transition with both electrodes
- Useful $\frac{1}{2}$ metals
 - High Curie temperature
 - Well behaved magnetism
 - Interface stability
 - Thermal stability
 - Defect tolerant
- d-d gap
 - Fe_3O_4
 - MnFe_2O_4
 - Singh PRB **65** 064432 (2002)
 - $\text{Fe}_x\text{Co}_{(1-x)}\text{S}_2$
 - Mazin APL **77** 3000 (2000)
- Charge transfer gap
 - CrO_2
 - Manganites
- Covalent gap
 - Semi-Heusler Family
 - NiMnSb
 - PtMnSb

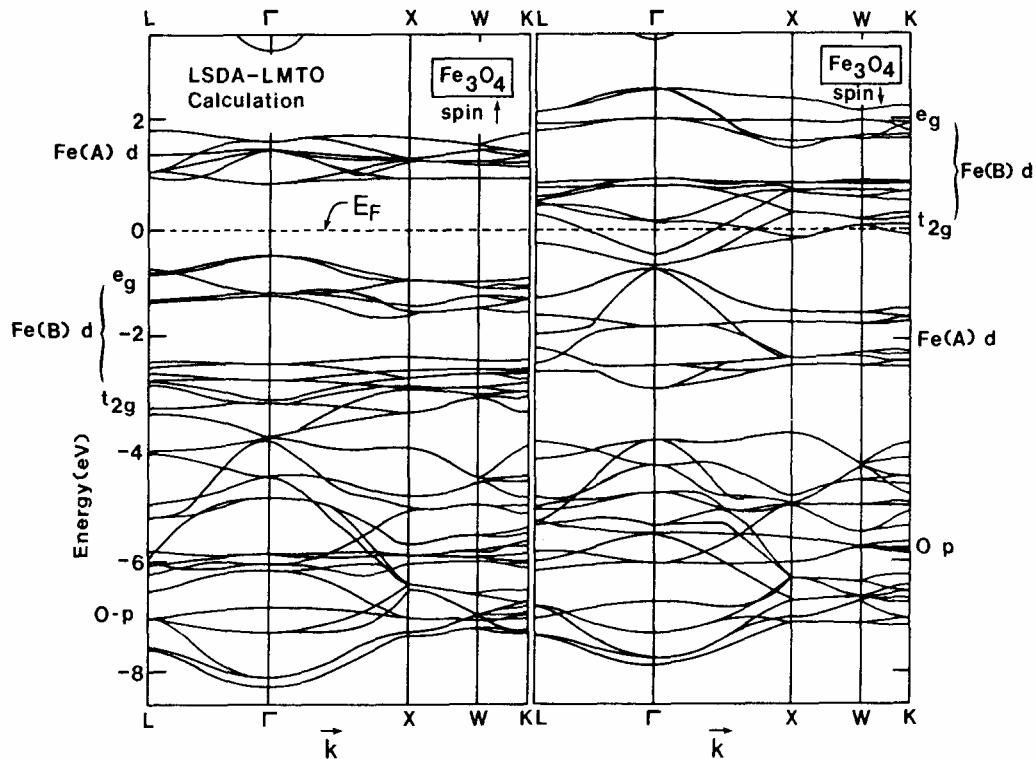
Feng J. Appl. Phys. 91 8340 (2002)

Crystal and Band Structure of Fe_3O_4



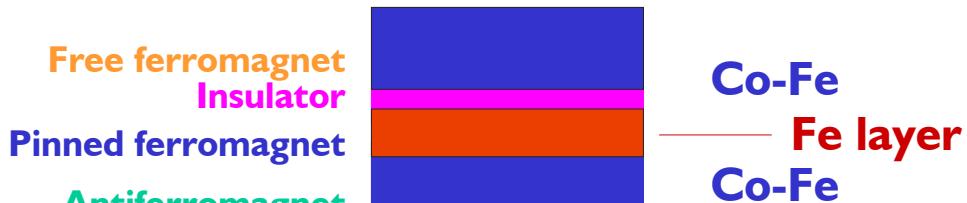
Yanase & Siratori, 1984

Inverse Spinel: fcc close packed O
A site: Tetrahedral Fe^{3+}
B site: Octahedral Fe^{3+} and Fe^{2+}

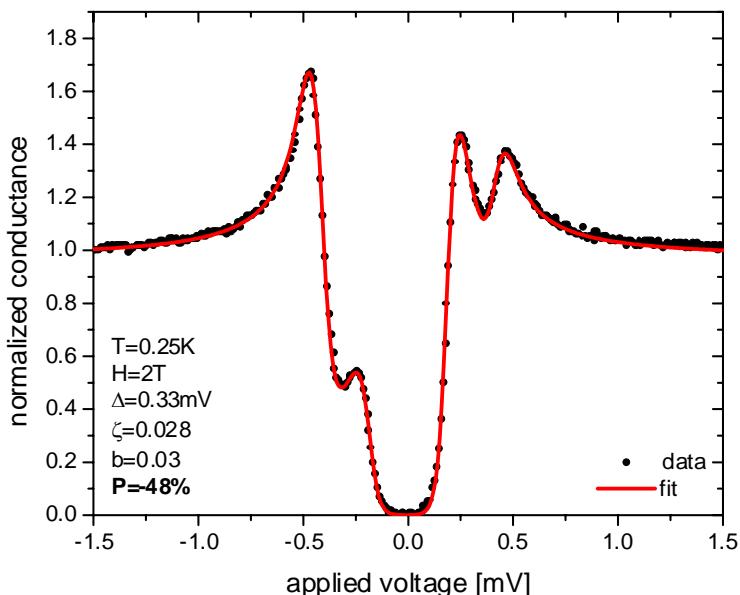


- ◆ Spin polarized electron bands from local spin density LMTO calculation [Zhang & Satpathy, 1991]
- ◆ Half metallic nature of Fe_3O_4 confirmed by recent fully relativistic first principles band structure calculations [Art Freeman]
- ◆ Only minority-spin electrons are present at the Fermi Energy

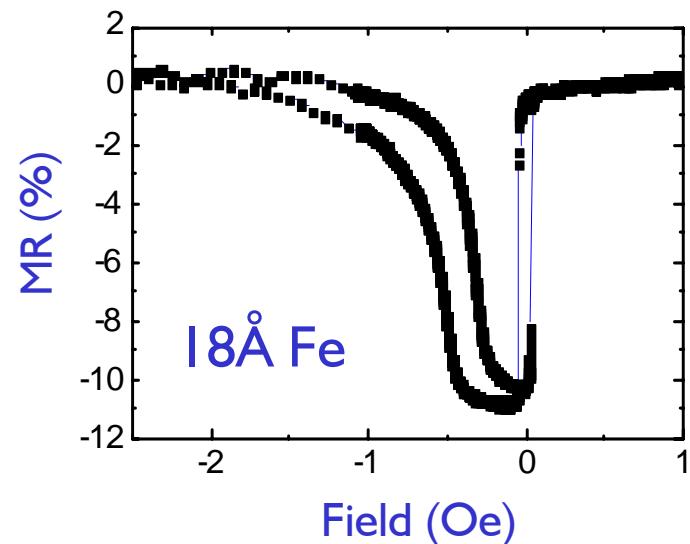
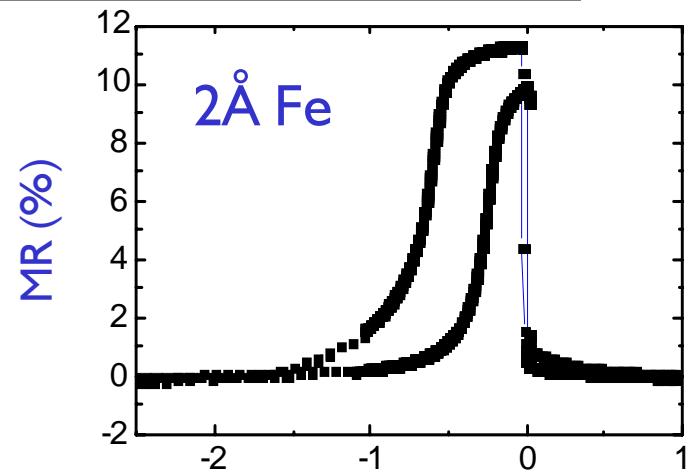
Magnetic Tunnel Junction with 24 Å MgO barrier: Normal and Inverse MR



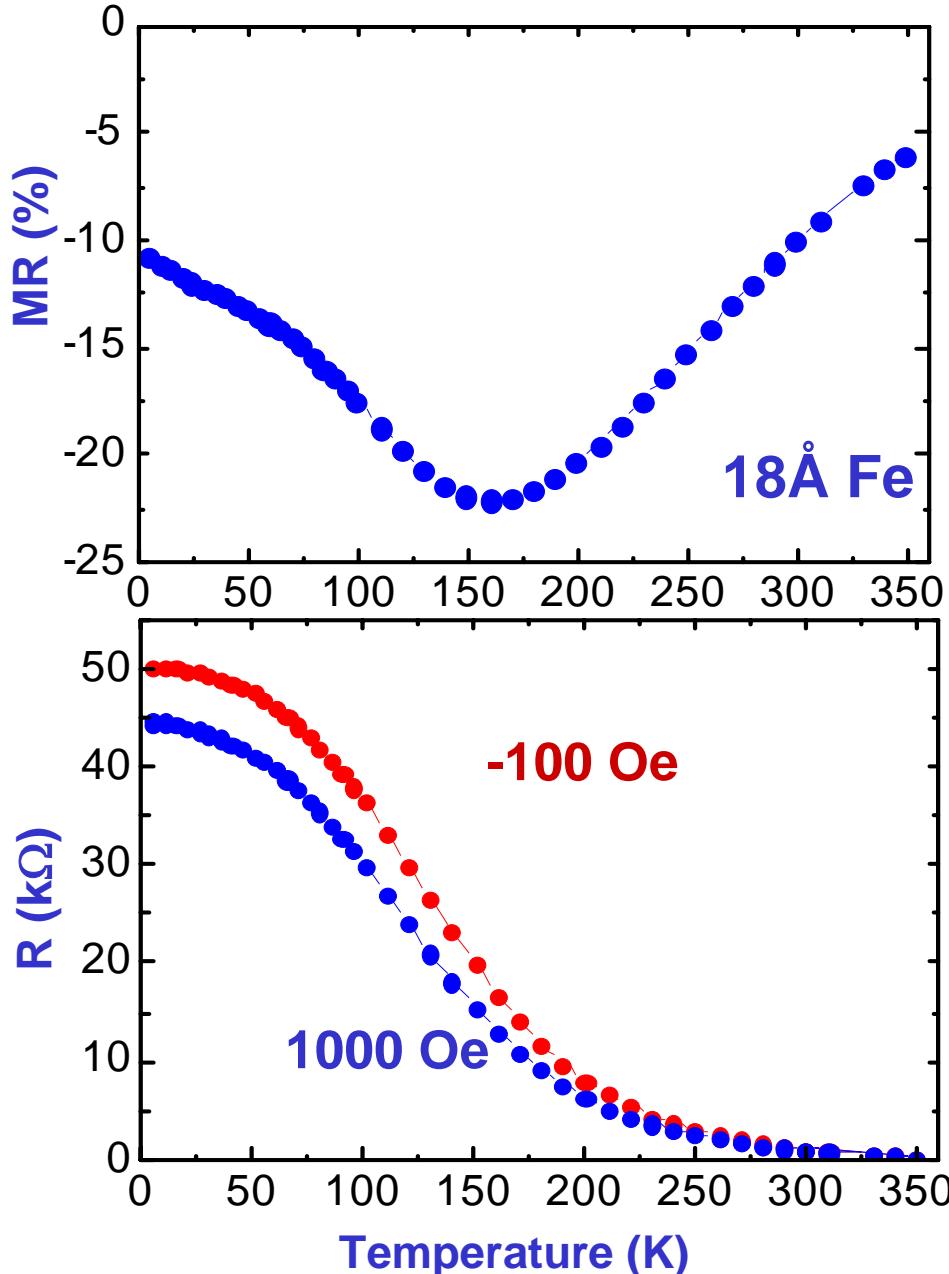
◆ negative spin polarization of -48%



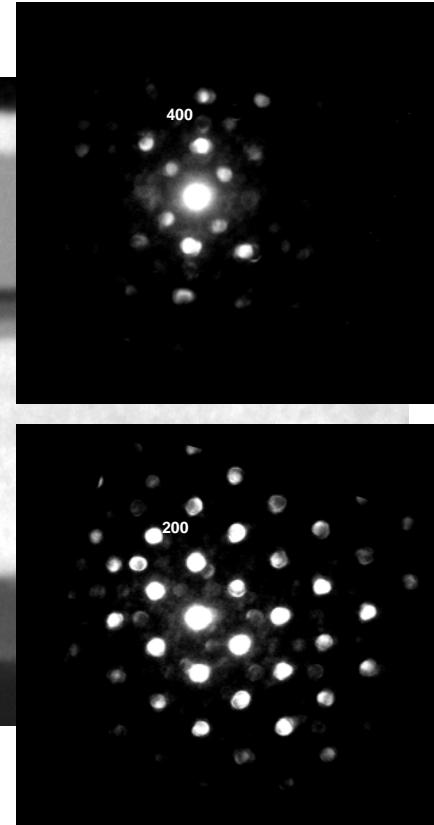
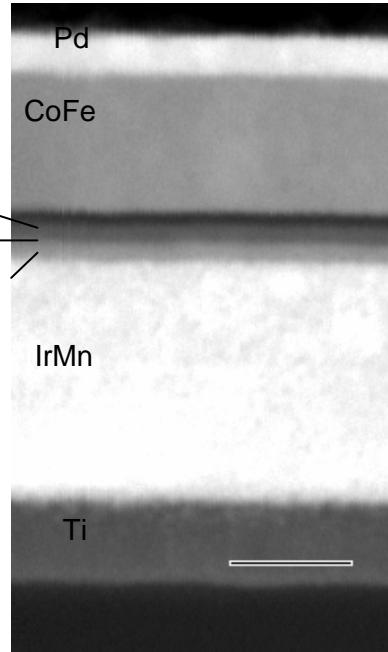
- ◆ Increased polarization for thicker layers of Fe_3O_4
- ◆ Magnetite layer is magnetically saturated as measurement is taken in an external field of 2T



MTJ with Fe_3O_4 Electrode



Al_2O_3
 FeO_x
 CoFe/Fe

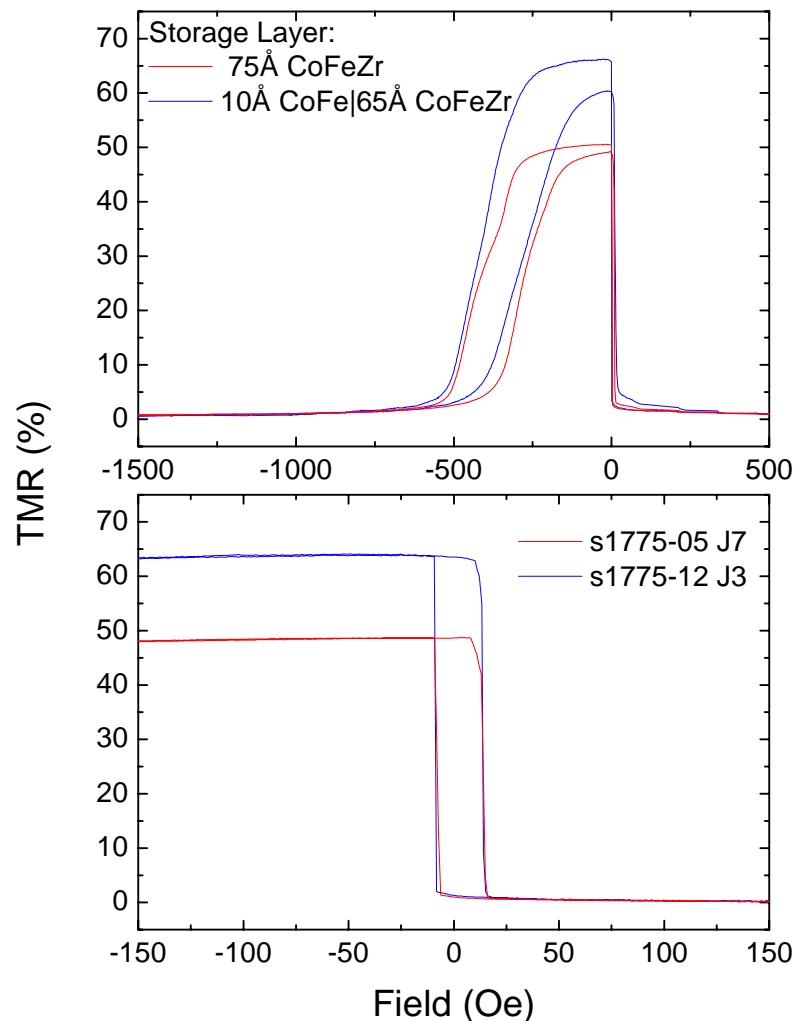


Energy filtered XTEM

- Thin [001] oriented Fe_3O_4 layer formed at interface between Fe and oxide barrier
- No TMR for [111] oriented Fe_3O_4

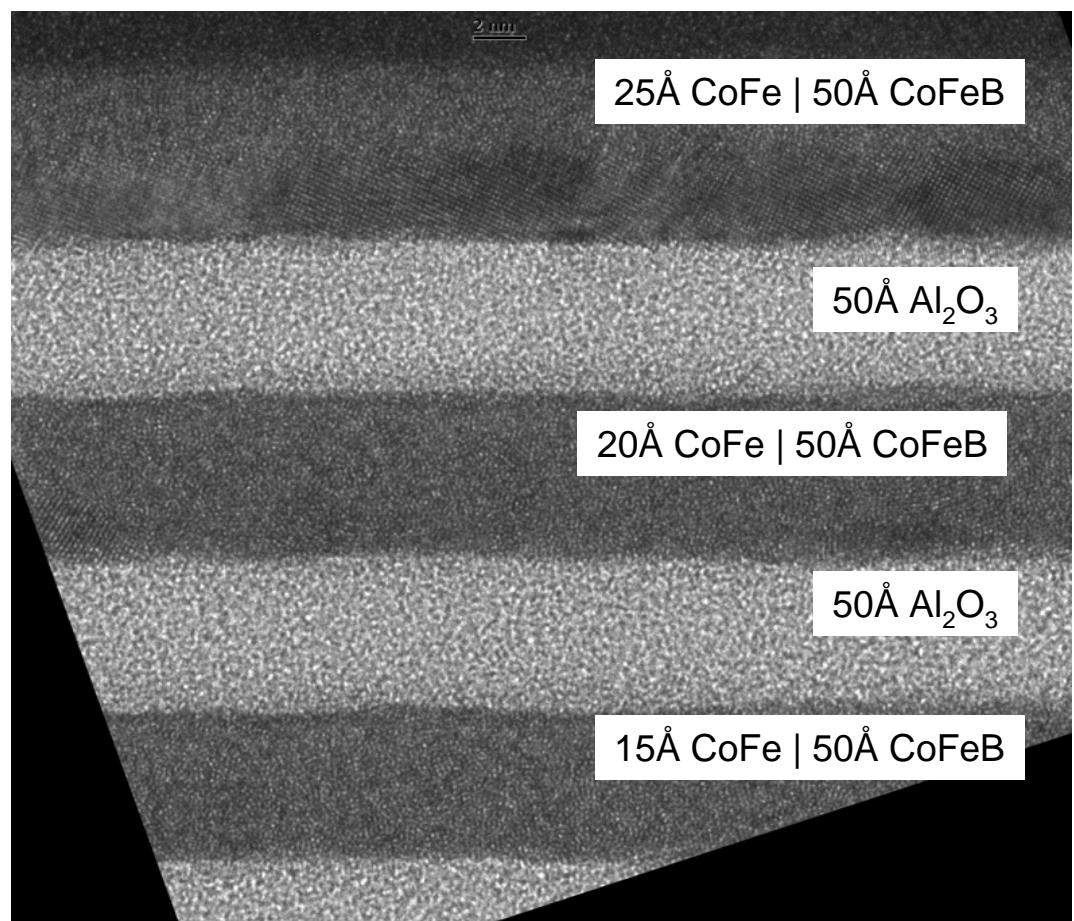
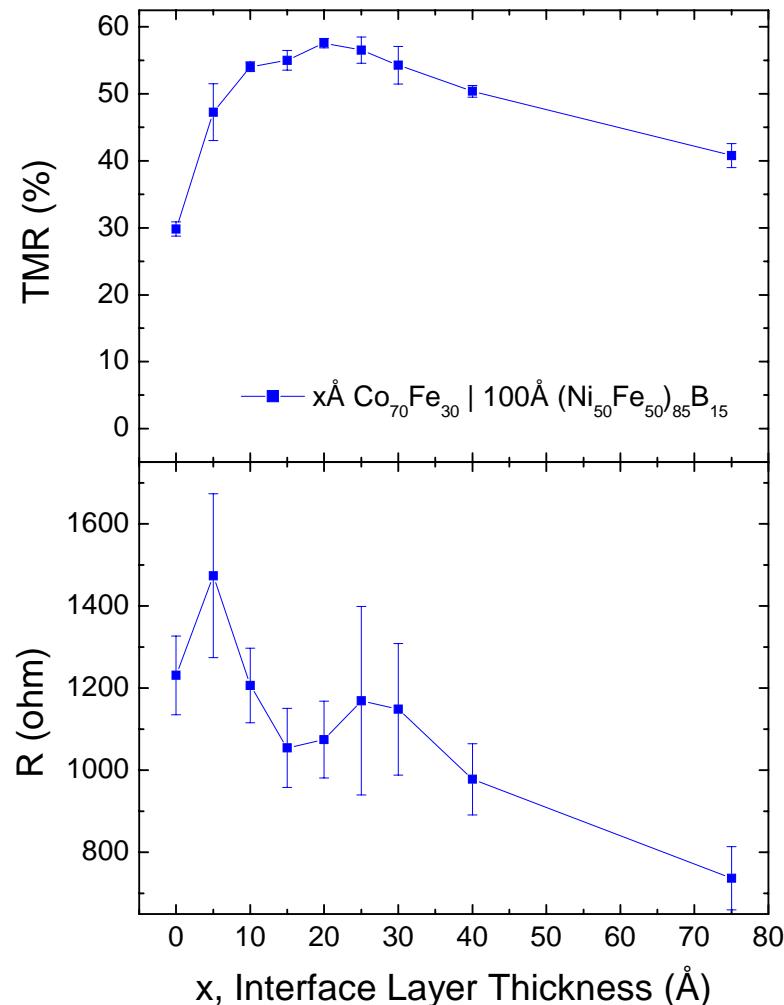
Amorphous ferromagnetic electrodes

- Why amorphous?
 - Low coercivity
 - Low magnetization
 - Uniform
 - Low magnetostriction
 - High thermal stability
- Loss of some spin polarization due to metalloid atoms
- Thin interface layer improves performance



Thin amorphous layers

- Thin CoFe layers are amorphous between Al_2O_3 and CoFeB for $t < 20 \text{ \AA}$

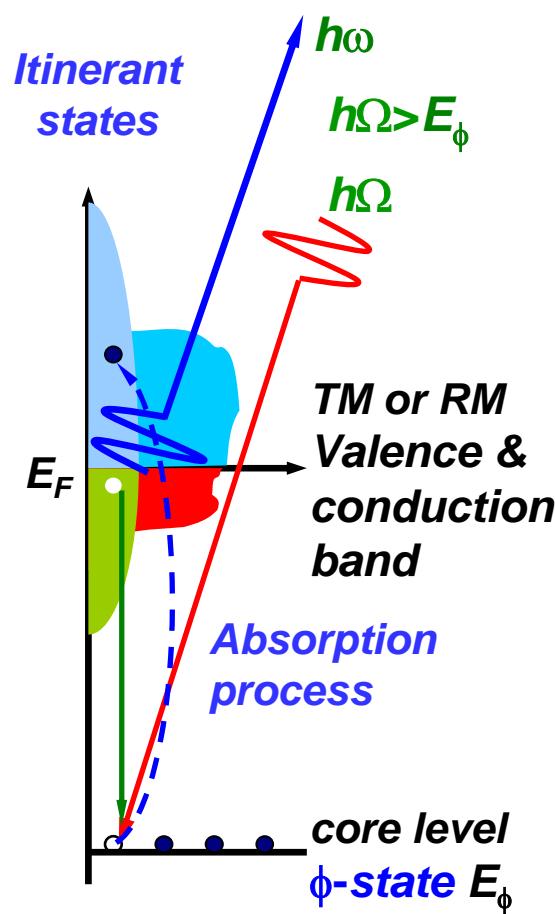


XTEM: Phil Rice

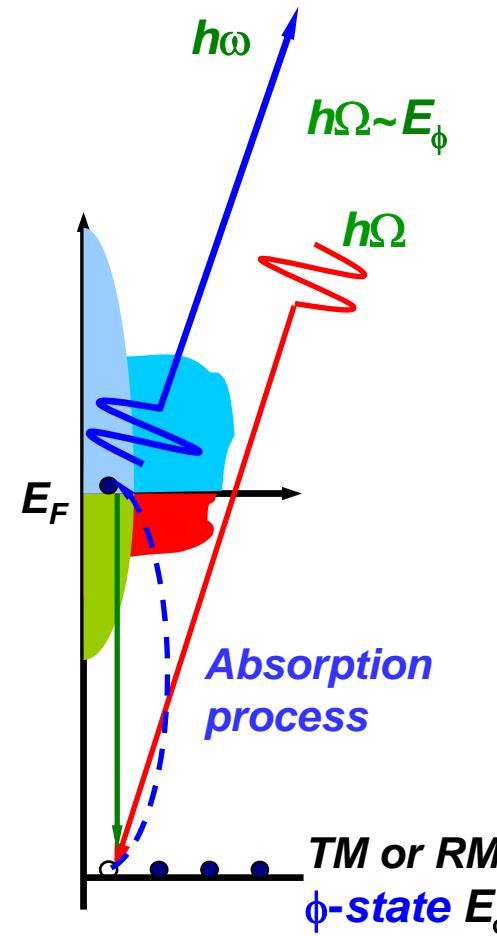
Stuart Parkin
July 7, 2003

Soft X-ray Emission Spectroscopy (SXES)

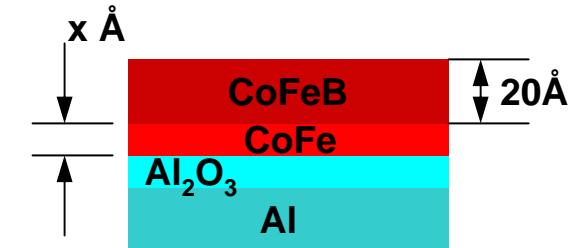
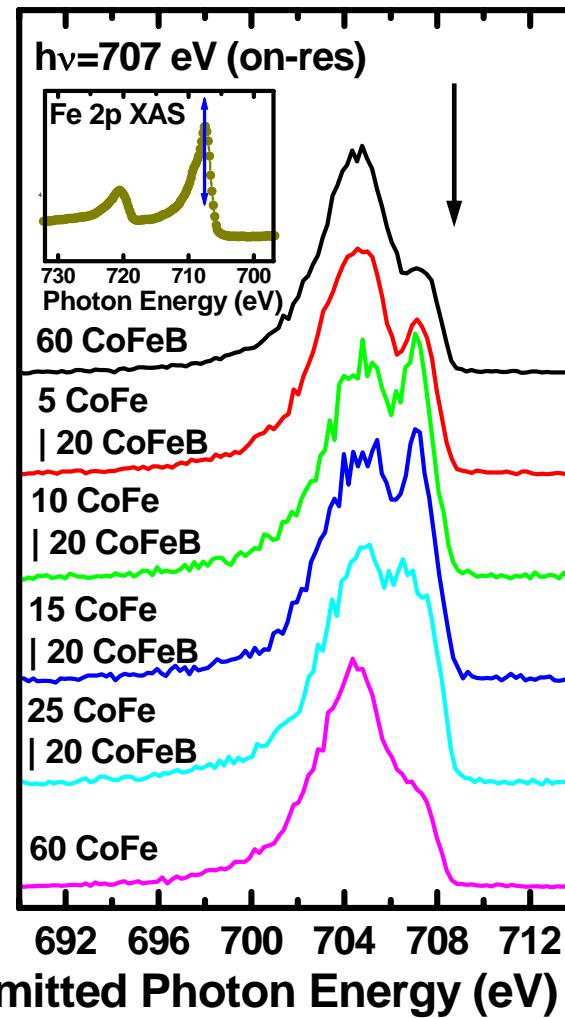
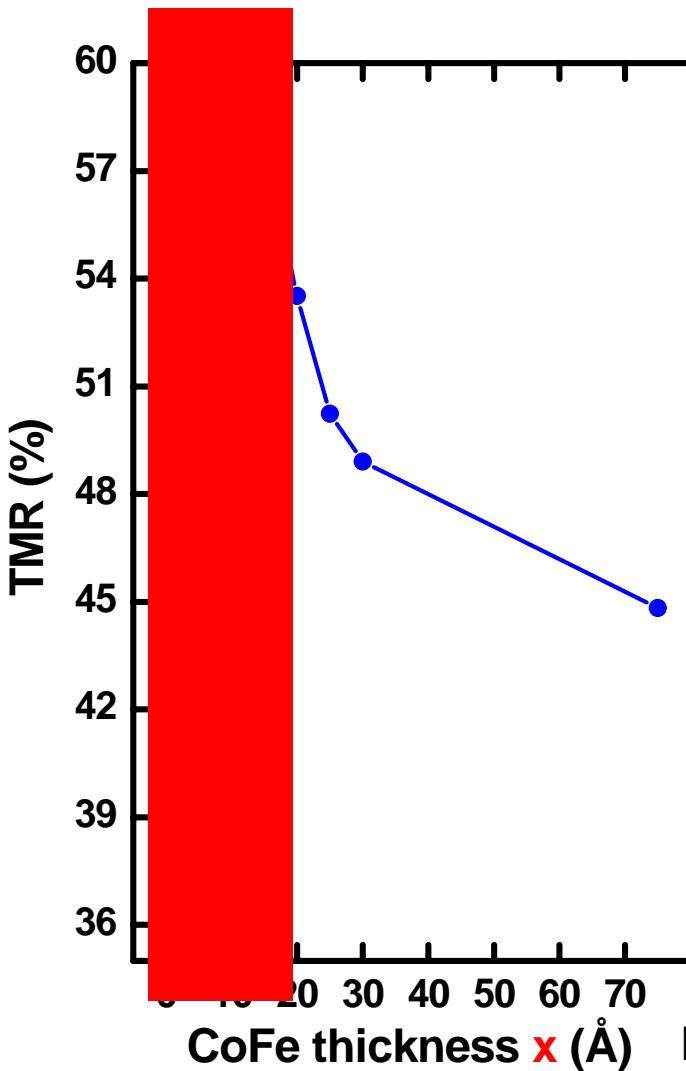
*conventional
x-ray fluorescence
→ partial local DOS*



*resonant x-ray emission
elastic scattering
(recombination)*



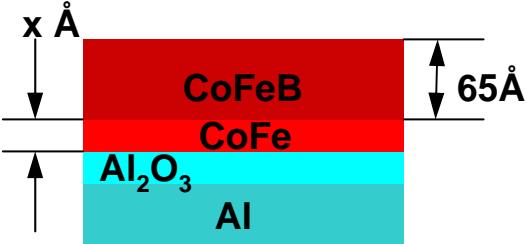
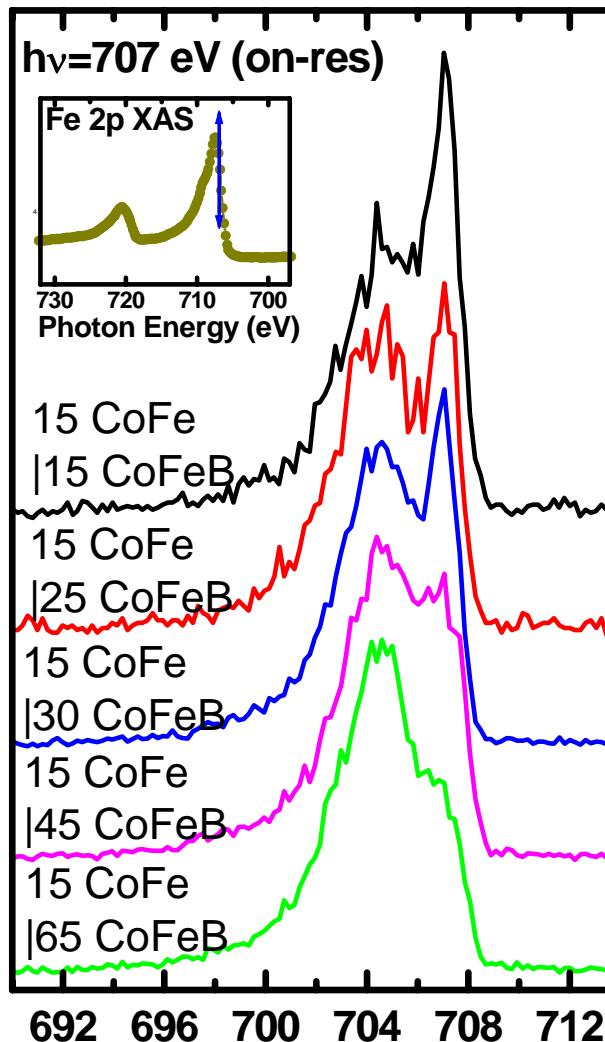
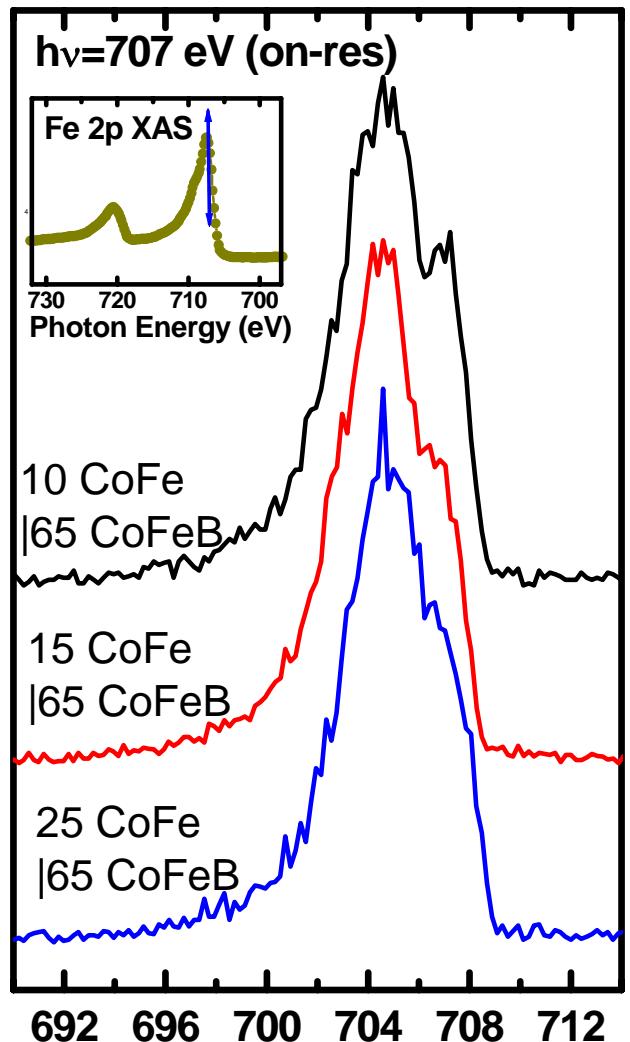
Resonant X-ray Emission Near Fe 2p edge



- Enhancement of spectral feature at Fermi level for on-resonant XES (Fe 3d partial DOS) at $x = 15\text{--}20 \text{ \AA}$ → same range of thickness for enhanced TMR
- V. L. Moruzzi et al. (1983) find enhanced dos for disordered CoFe

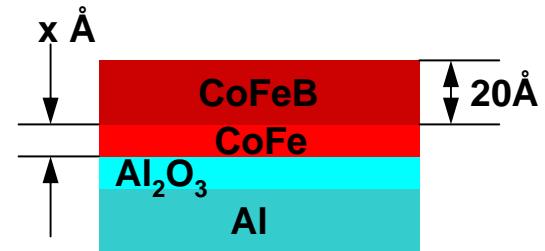
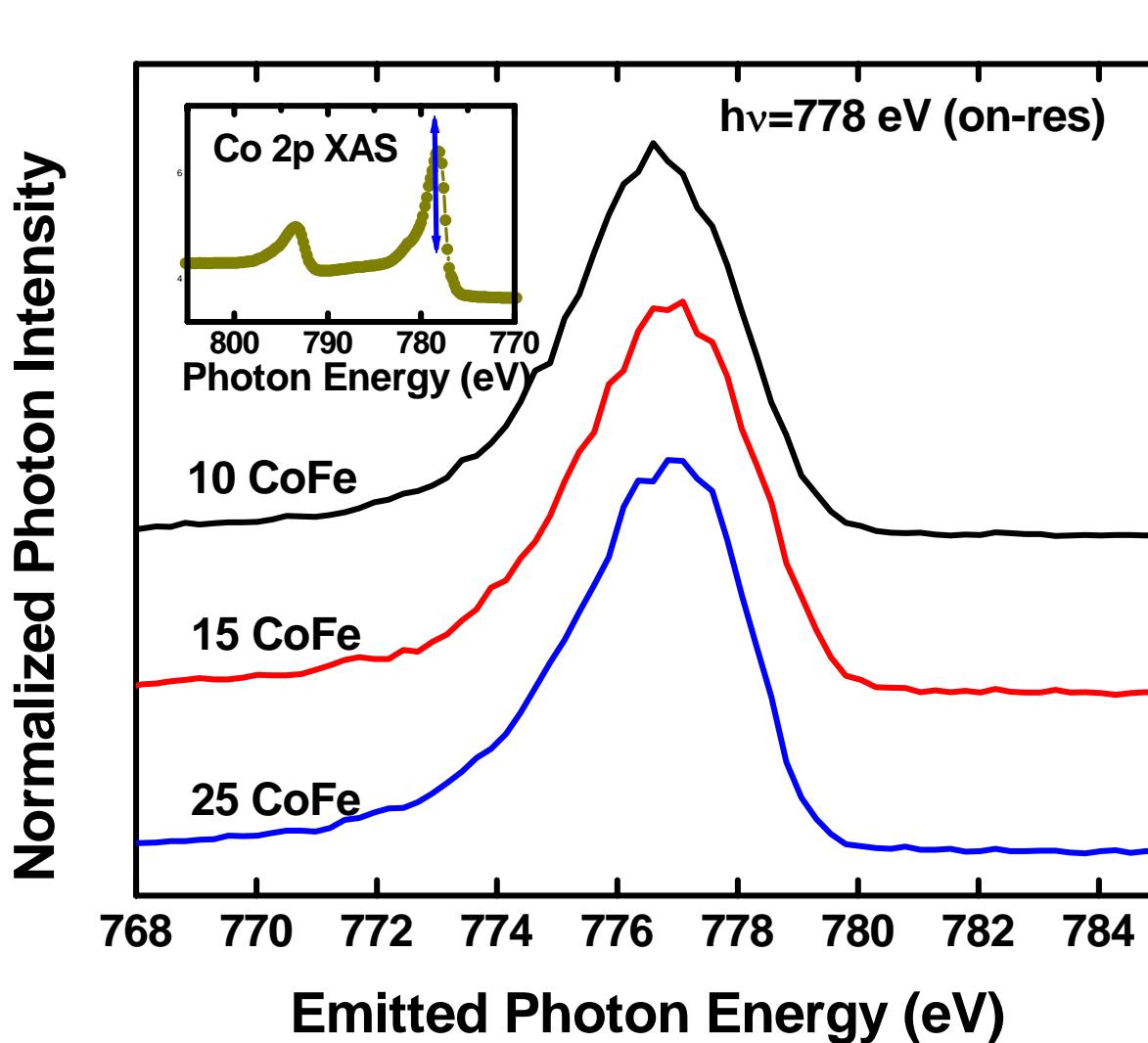
Resonant X-ray Emission Near Fe 2p Edge

Normalized Photon Intensity



Enhancement decreases as CoFeB thickens → evidence that spectral feature enhancement is due to CoFe interface layer

Resonant x-ray emission near Co 2p edge



- no change of Fermi level feature → evidence that Co LDOS does not change at Fermi level with amorphization; consistent with unchanged Co local magnetic moment in CoFe alloys

[C. Paduani et al, J.A.P. 86, 578 (1999); J. M. MacLaren et al, JAP 85, 4833 (1999)]

Why are Magnetic Tunnel Junctions Interesting?

Perpendicular current flow

→ ideal for ultra high density recording (narrow read gap)

Much wider range of materials possible (c.f. GMR)

Interfacial phenomenon: very thin stacks (c.f. GMR)

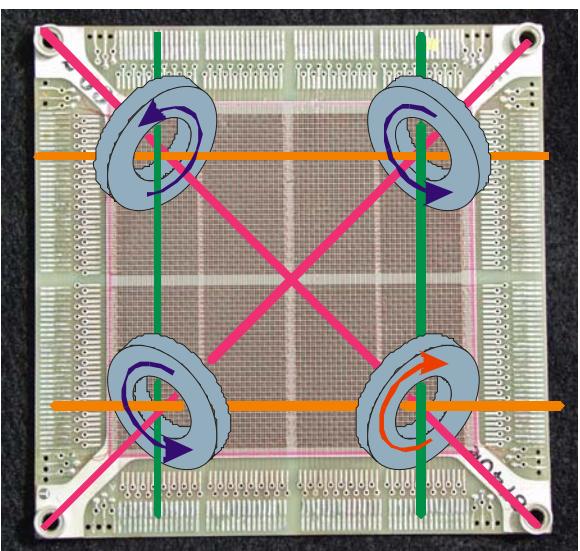
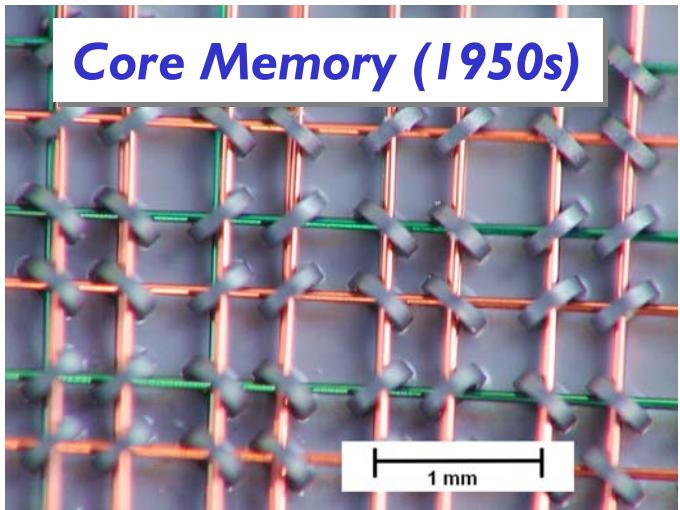
Weak temperature dependence

No theoretical limit to Tunneling Magnetoresistance!

- ◆ GMR: 1990: 10%; Today: 15-20% (simple spin valve)
- ◆ TMR: 1975: 2% (4K); 1995: 10% ; 1997: 48%;
Today: >220% at 300K

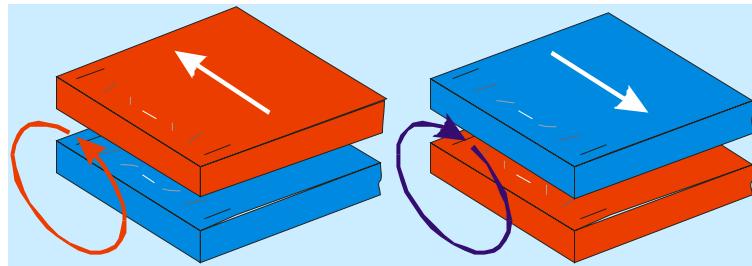
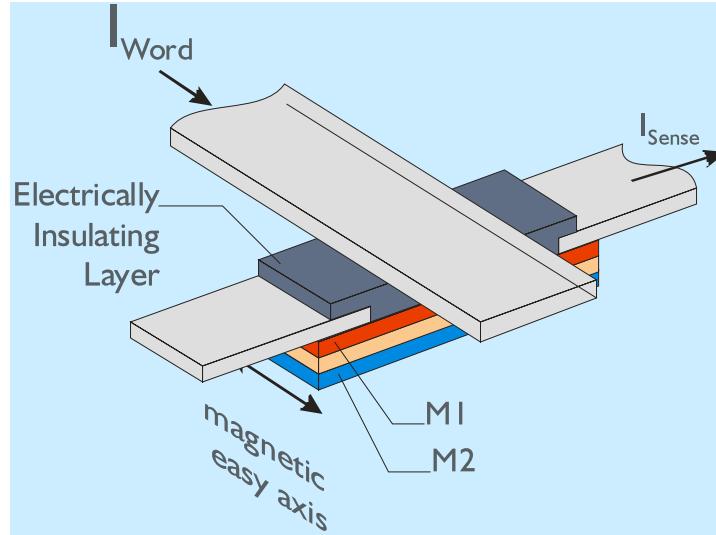
→Magnetic Tunnel junctions: game-changer!

Previous MRAM Approaches: Ferrite Core and AMR RAM



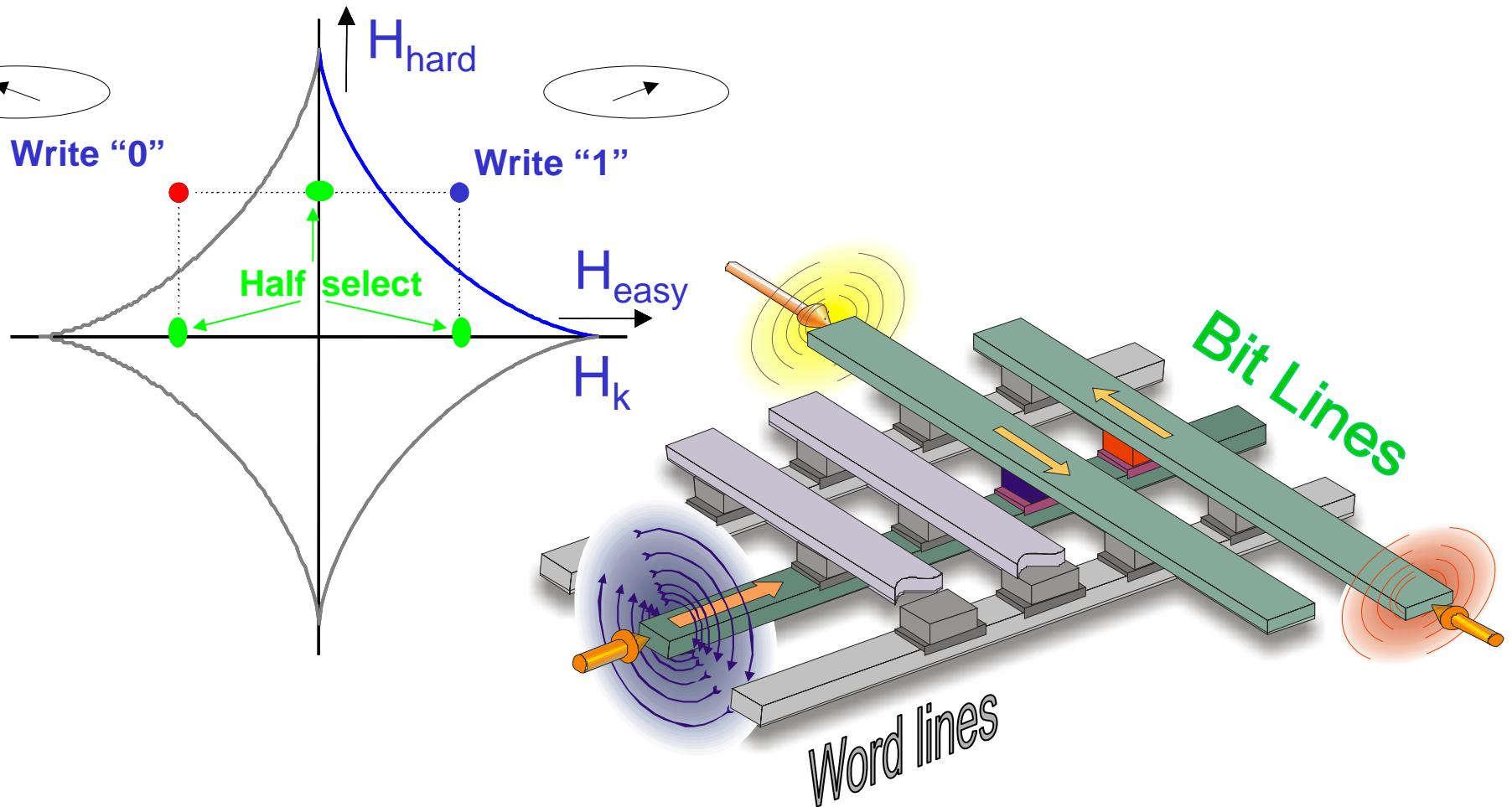
2-D array of ferrite cores with write
and sense wires

Anisotropic MR (AMR) Memory (1980s)

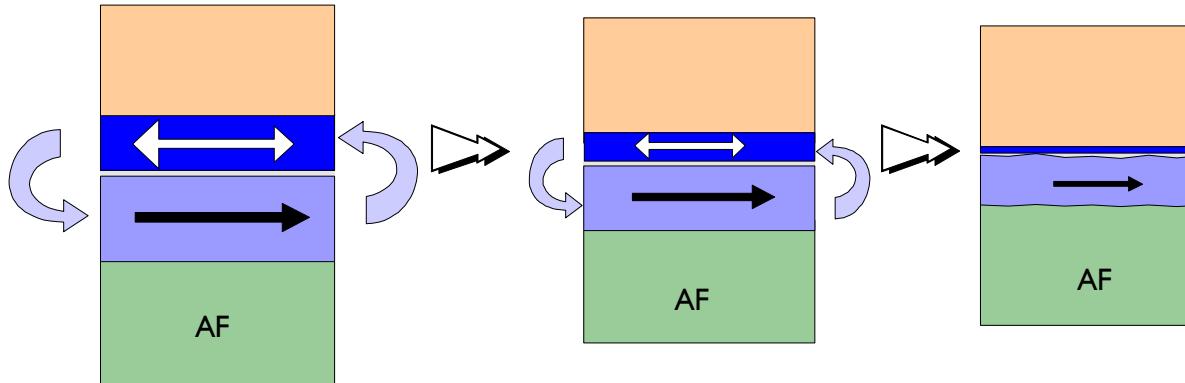


Flux closed pair of
magnetic thin films

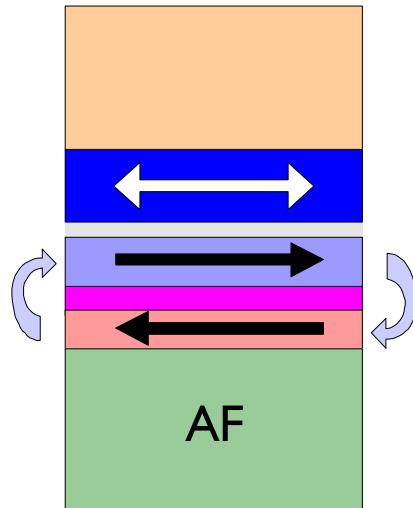
Cross-point Architecture: Coincident Field Selection for Writing MTJ Cell



Flux Closure Issues and Remedies in MTJs



Reduce magnetostatic interaction → reduce FM layer thicknesses

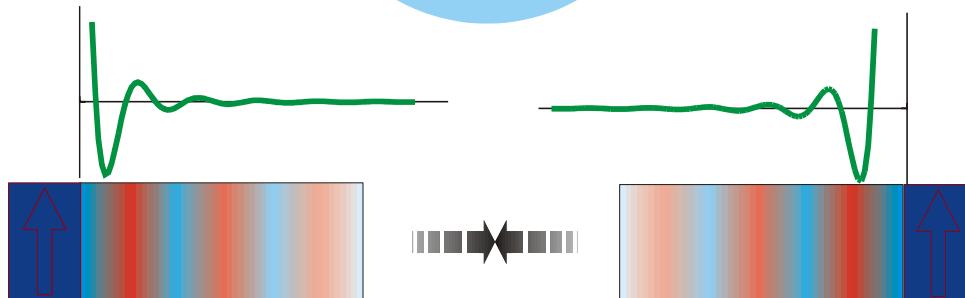
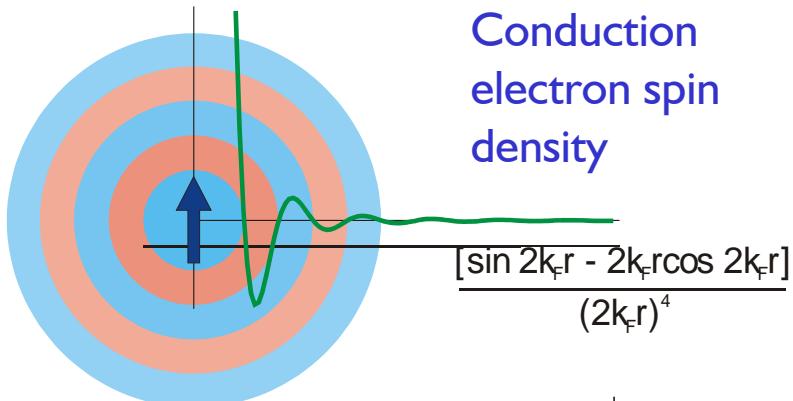


**Use AP (Anti-parallel) pinned FM layer
e.g. FM/Ru or FM/Os**

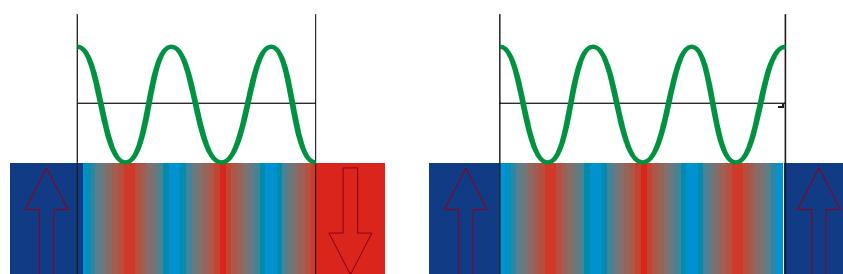
Ref: Parkin & Heim, US patent #5,465,185 (filed 1991)
Parkin US patent (filed 1998)

Indirect Exchange Coupling via non-magnetic metals

RKKY coupling:
magnetic impurity in
nonmagnetic metal



Spin density wave from
scattering at interface
between magnetic and non-
magnetic layers



Coupling of magnetic
layers via non-magnetic
spacer: sign, magnitude
depend on spacer
thickness

First Observation of Oscillatory Coupling and GMR in Metallic Multilayers
Parkin et al, Phys. Rev. Lett. 64, 2304 (1990)

Oscillatory coupling - Ru

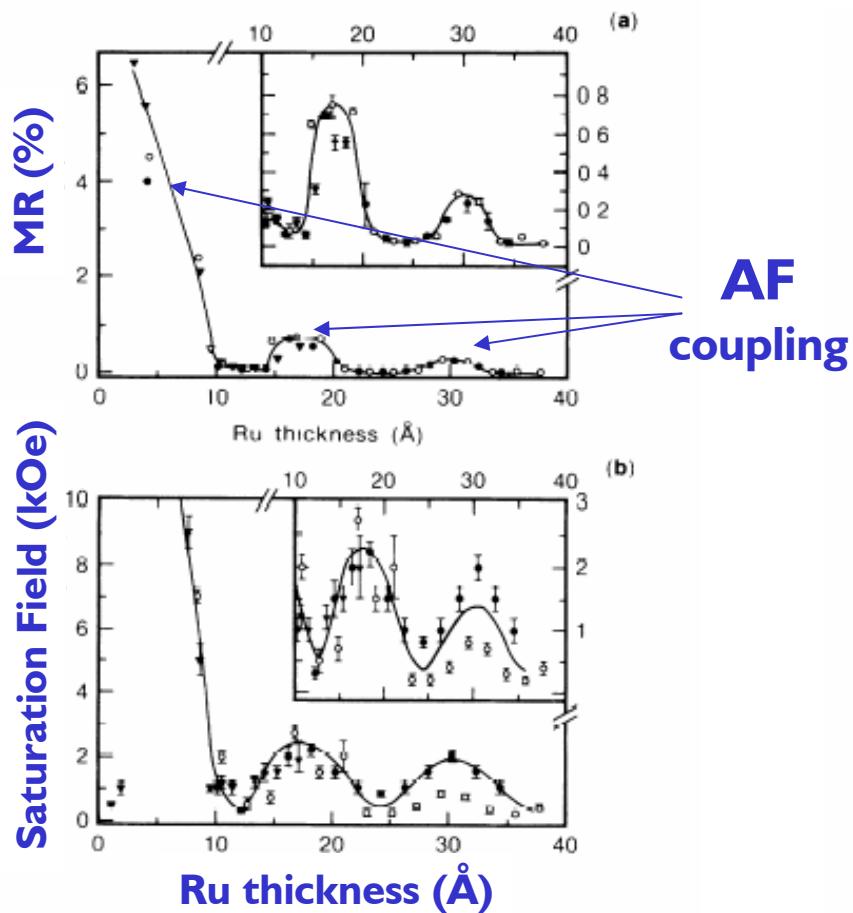


FIG. 3. (a) Transverse saturation magnetoresistance (4.5 K) and (b) saturation field (300 K) vs Ru layer thickness for structures of the form Si(111)/(100 Å) Ru/[20 Å] Co/ t_{Ru} Ru₂₀/(50 Å) Ru deposited at temperatures of ●, 40°C; ○, 125°C; ×, 200°C.

Oscillatory coupling - Cr

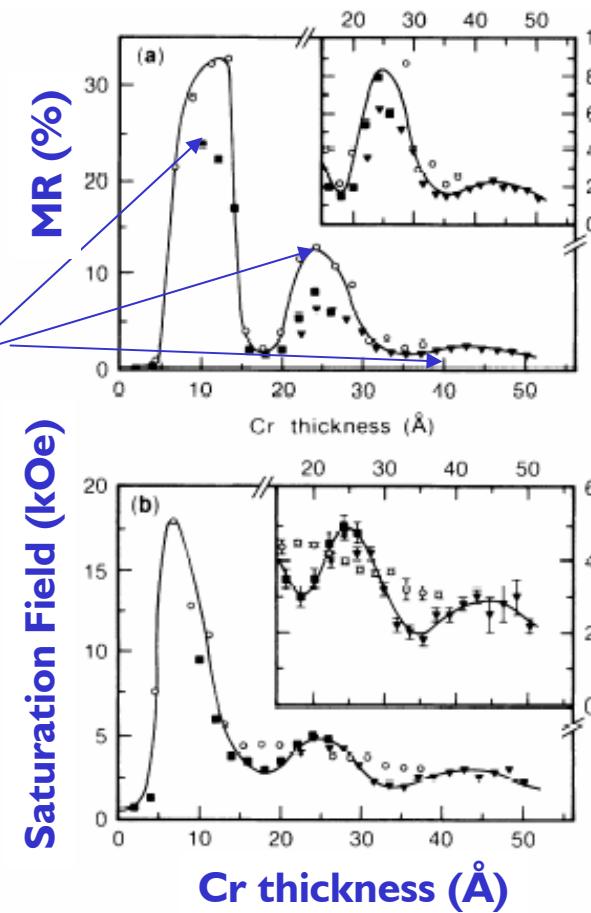
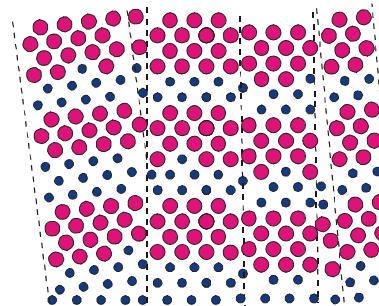
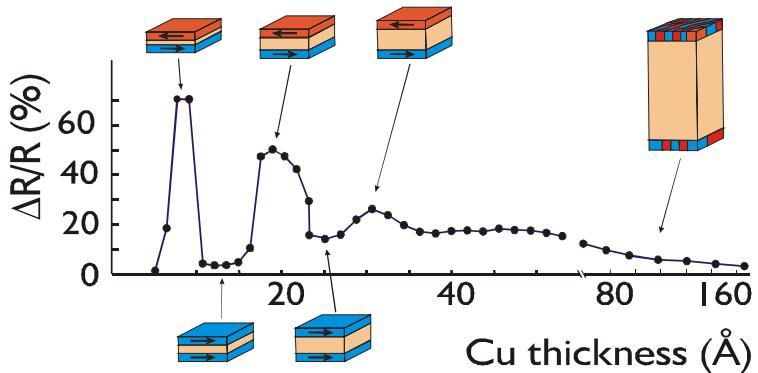
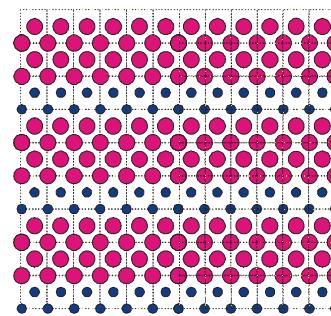
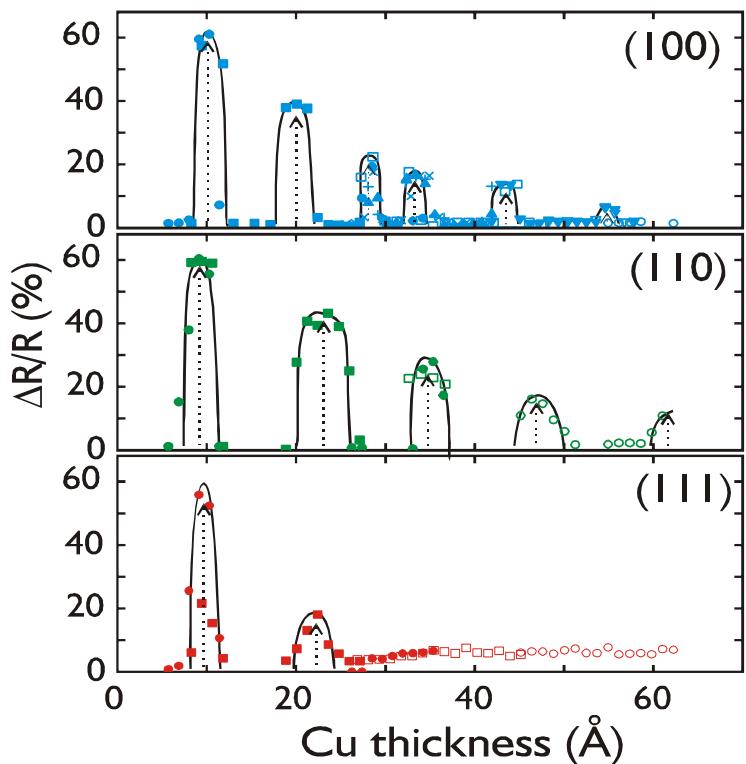


FIG. 4. (a) Transverse saturation magnetoresistance (4.5 K) and (b) saturation field (4.5 K) vs Cr layer thickness for three series of structures of the form Si(111)/(100 Å) Cr/[20 Å] Fe/ t_{Cr} Cr_N/(50 Å) Cr, deposited at temperatures of △, ■, 40°C ($N=30$); ○, 125°C ($N=20$).



Polycrystalline

S.S.P. Parkin et al,
Phys. Rev. Lett. **66**, 2152 (1991)



Single crystalline

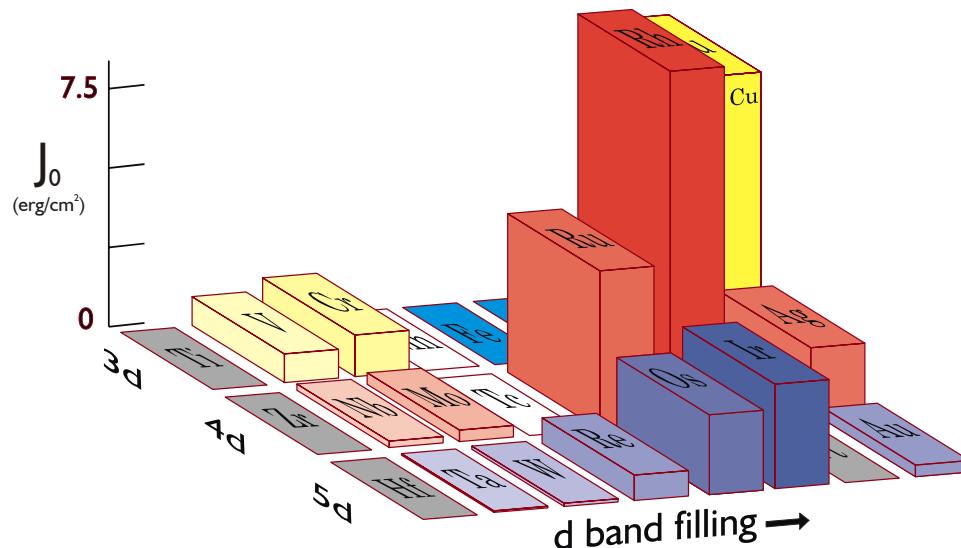
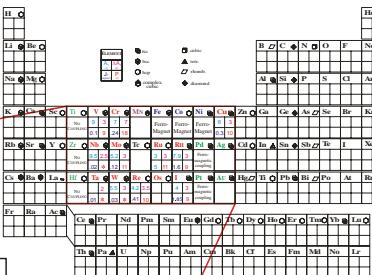
S.S.P. Parkin

Sputter deposited on MgO(100), MgO(110) and Al₂O₃ (0001) substrates using Fe/Pt seed layers deposited at 500C and Co/Cu at ~40C

**Oscillations in GMR:
Polycrystalline vs. Single
Crystal Co/Cu
Multilayers**

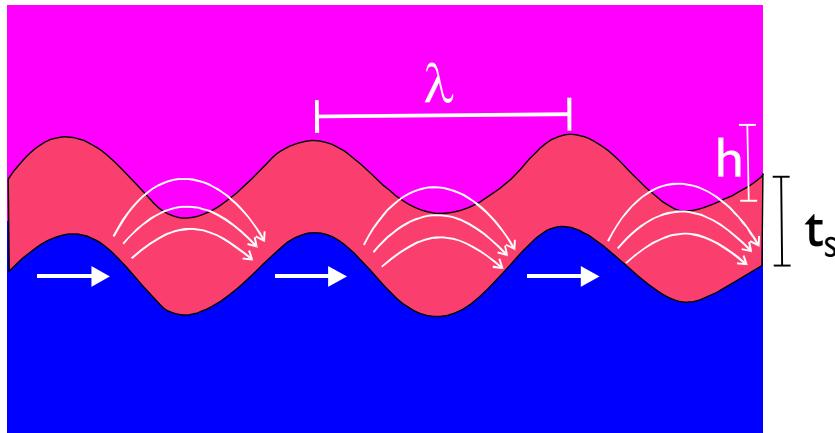
Oscillatory Exchange Coupling Strength: Variation across Periodic Table

ELEMENT		FCC	bcc	hcp	complex cubic
A ₁ (Å)	ΔA ₁ (Å)				
J ₁ (erg/cm ²)	P (Å)				
Ti	○	V	◊	Cr	◊
Mn	◊	Fe	◊	Co	○
Ni	◊	Cu	◊		
		FERRO-MAGNET		FERRO-MAGNET	
				FERRO-MAGNET	
Zr	○	Nb	◊	Mo	◊
Tc	○	Ru	○	Rh	◊
		Pd	◊	Ag	◊
		FERRO-MAGNETIC COUPLING			
Hf	○	Ta	◊	W	◊
		RE	○	Os	○
		Ir	◊	Pt	◊
		Au	◊		
		FERRO-MAGNETIC COUPLING			



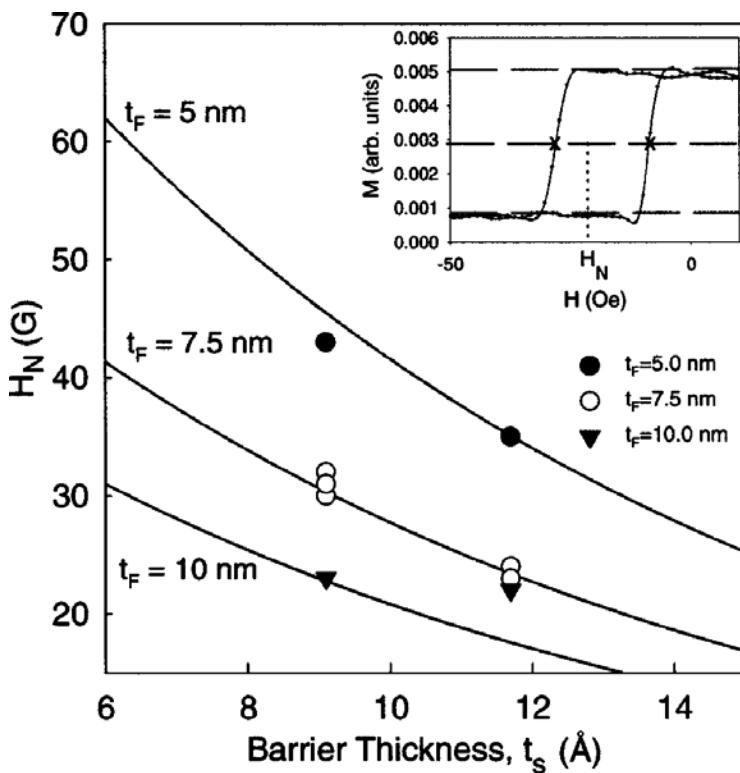
Ref: S.S.P. Parkin,
Phys. Rev. Lett. 67, 3598 (1991)

Néel Orange-peel Coupling



Correlated roughness
leads to
ferromagnetic
coupling

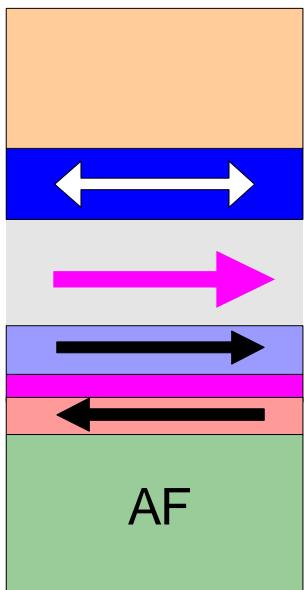
Néel coupling field $\rightarrow H_N = \frac{\pi^2}{\sqrt{2}} \left(\frac{h^2}{\lambda t_F} \right) M_s \exp(-2\pi\sqrt{2}t_s/\lambda)$



Coupling field, H_N , decreases with increasing thickness of ferromagnetic layer and tunnel barrier

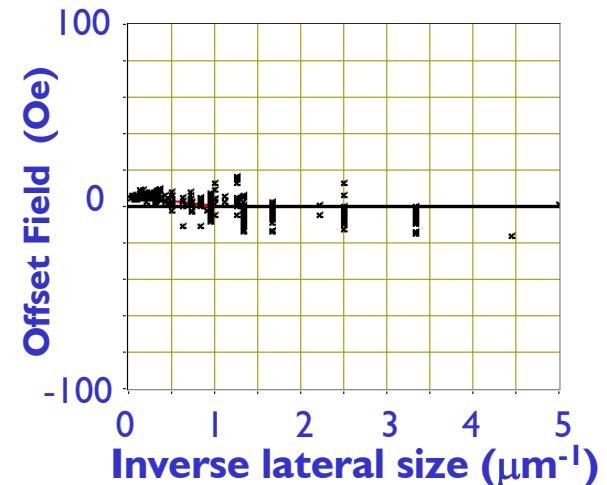
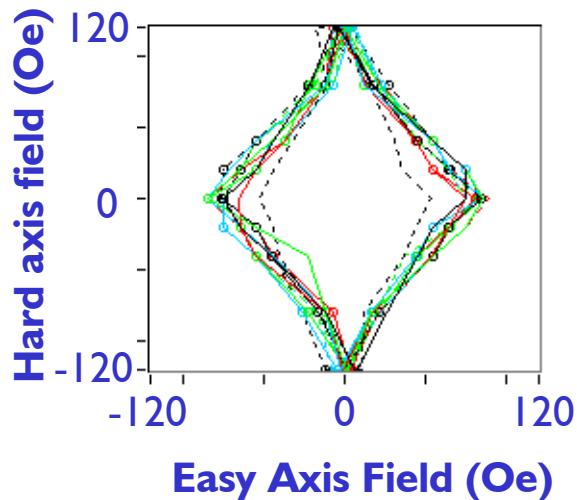
Schrag et al Appl. Phys. Lett. (2000)

Balancing Néel and Magnetostatic Fields in MTJs using Oscillatory Interlayer Coupling



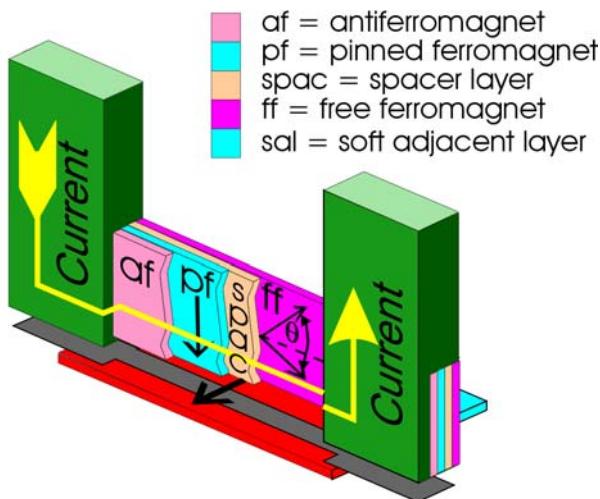
The magnetic hysteresis loop offset field is tuned to zero by balancing the dipolar and Neel coupling fields

Chiplet CA, $0.375 \times 0.75 (\mu\text{m})^2$



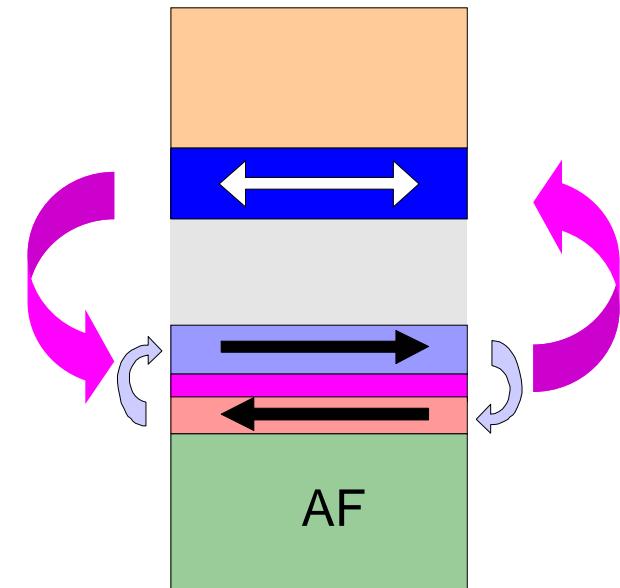
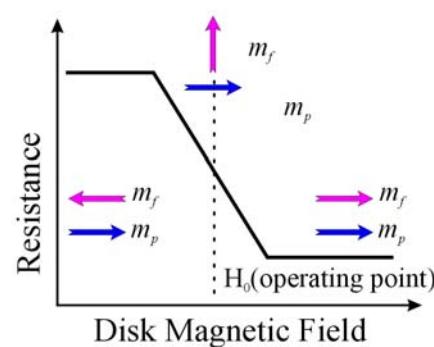
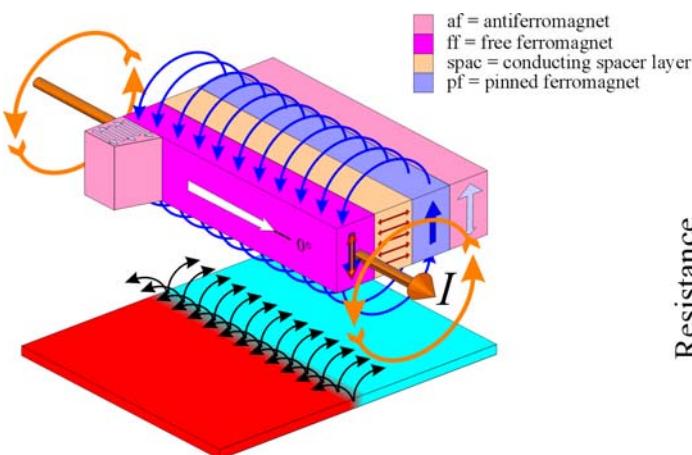
- MTJs with Improved Magnetic Switching Characteristics
 - using anti-parallel pinned (AP) ferromagnetic layer
 - Patterned AP pinned MTJ structures display highly symmetric astroid with no offset field

Giant Magnetoresistance Head

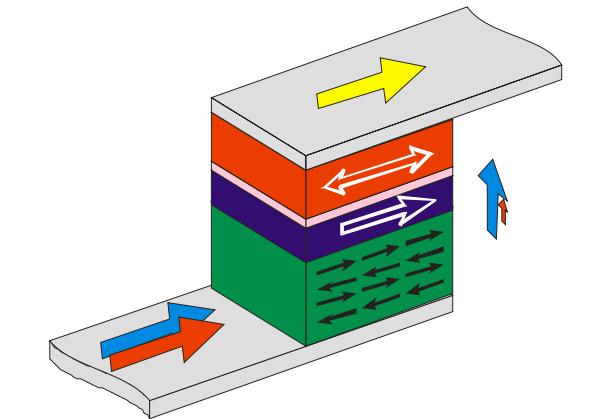
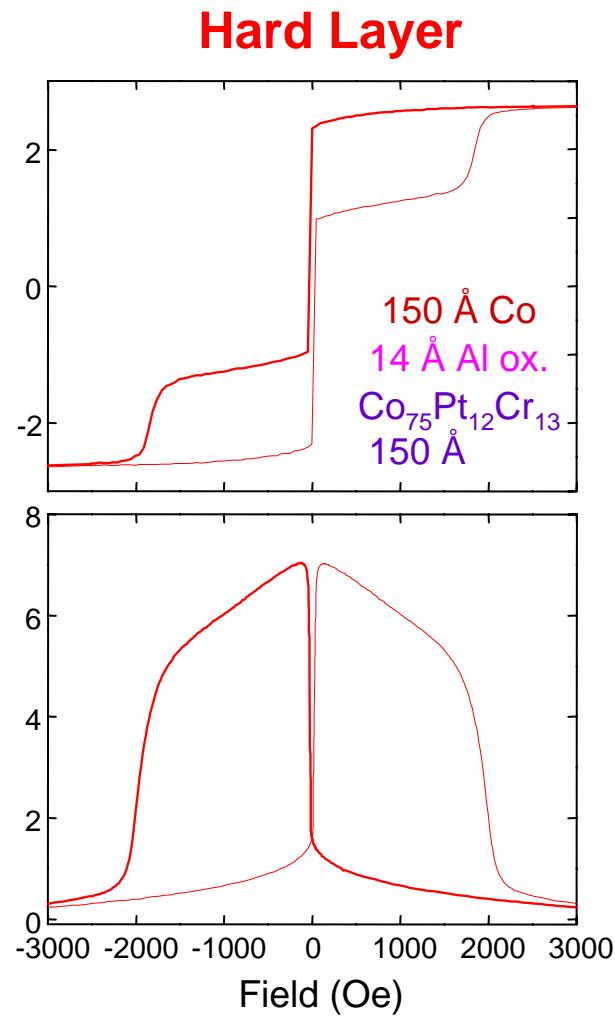
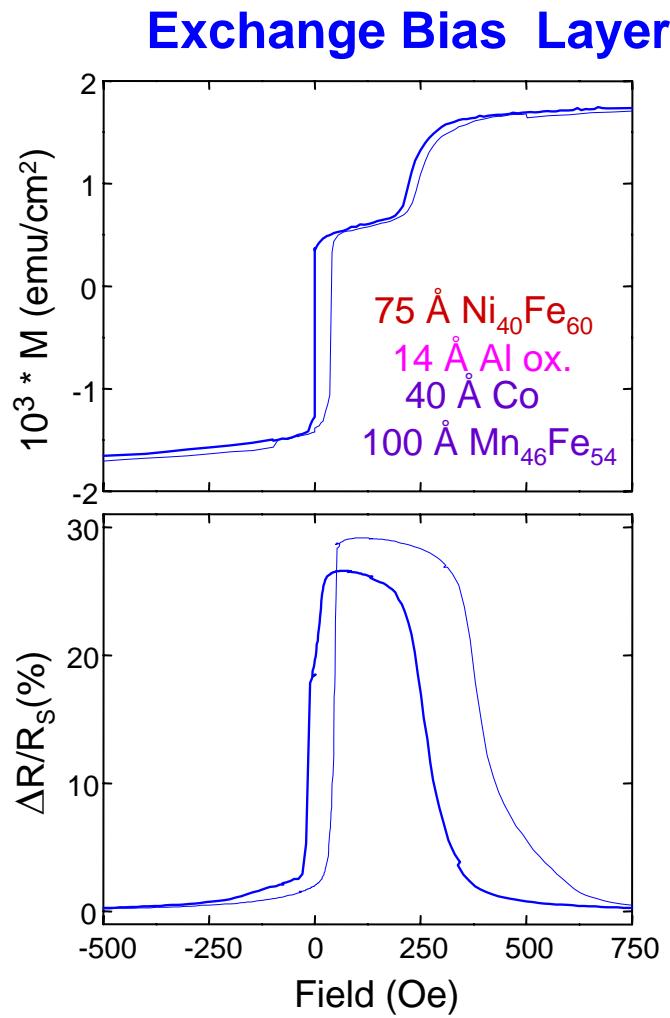


Current spin valve GMR head uses

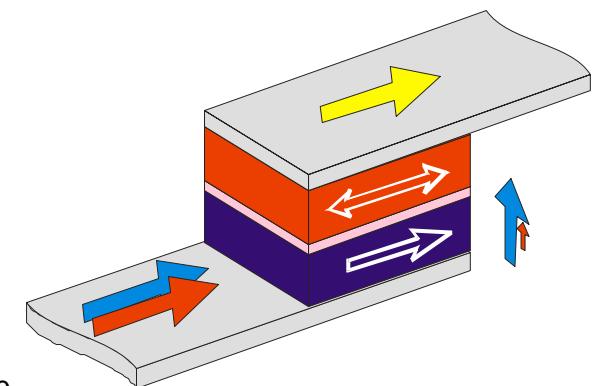
- PtMn exchange bias layer
- CoFe/Ru/CoFe pinned layer
- Cu spacer layer
- CoFe/NiFe free layer
- Various underlayers and overlayers



Magnetization Creep in Exchange Biased and Hard/Soft MTJ

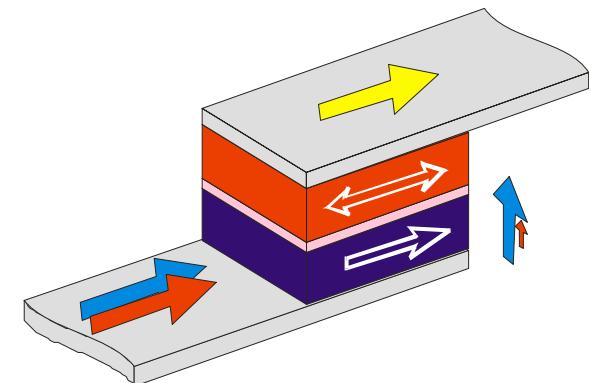
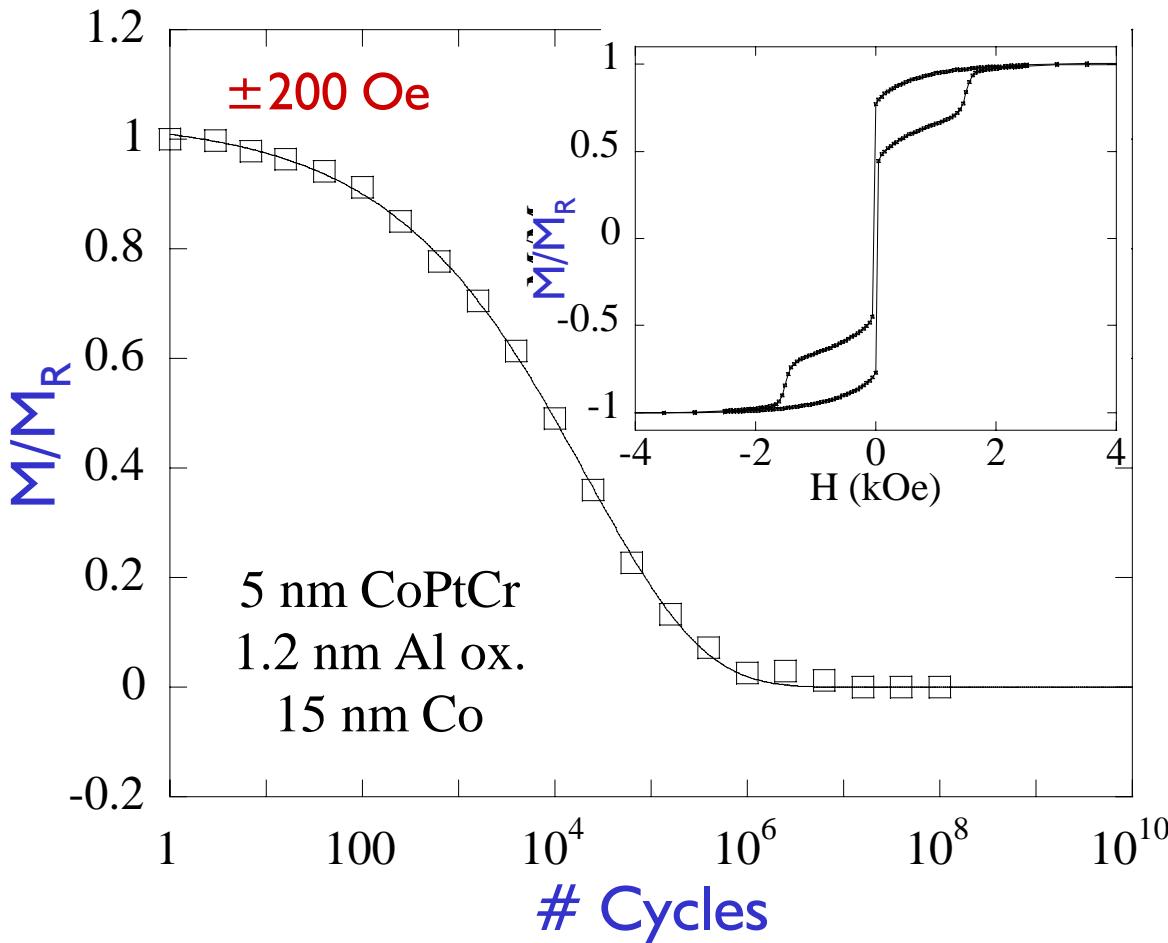


Exchange Biased



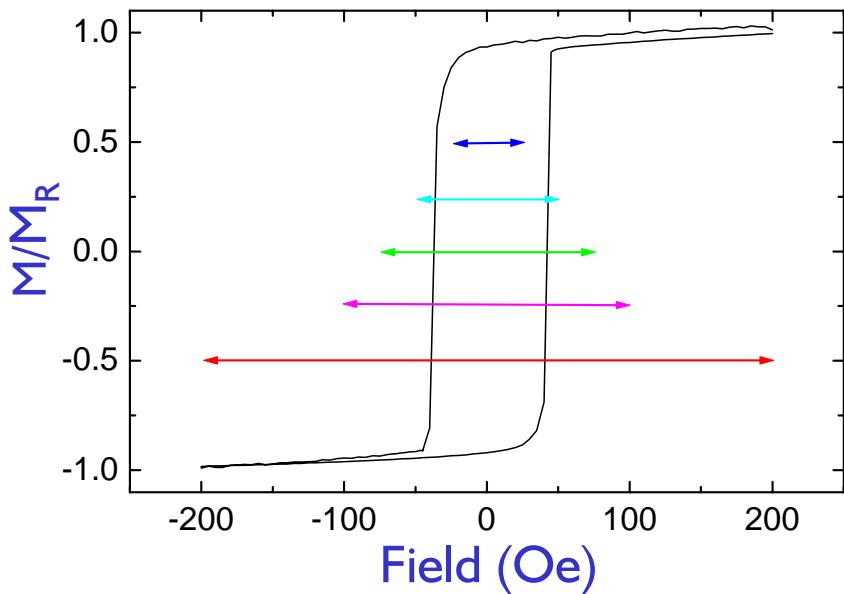
Hard/Soft

Magnetization Creep in Hard/Soft MTJ

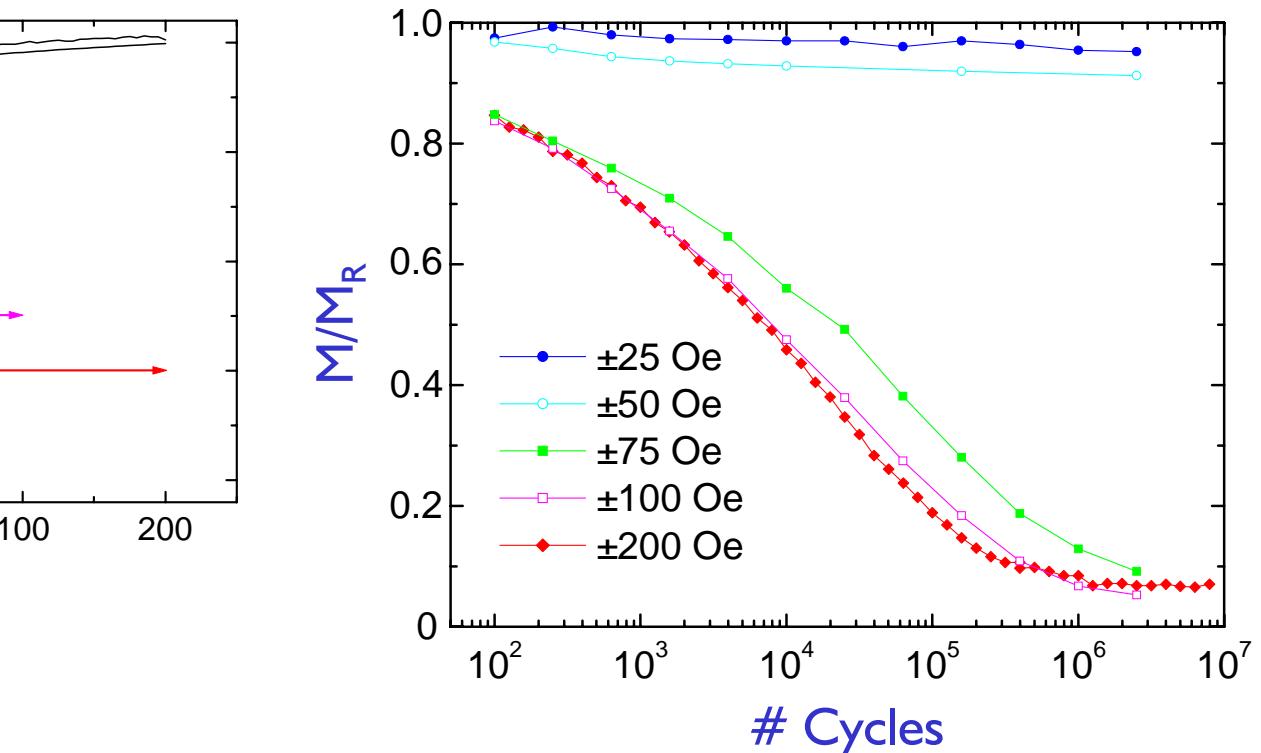


- ◆ Moment of hard layer decreases as moment of soft layer reversed
- ◆ Eventually soft layer completely demagnetizes hard layer
- ◆ Remanent moment decay follows a stretched exponential curve
- ◆ Decay is independent of cycling frequency up to 10 kHz
- ◆ Exchange biased MTJs stable to field cycling

Magnetization Creep in Hard/Soft MTJ



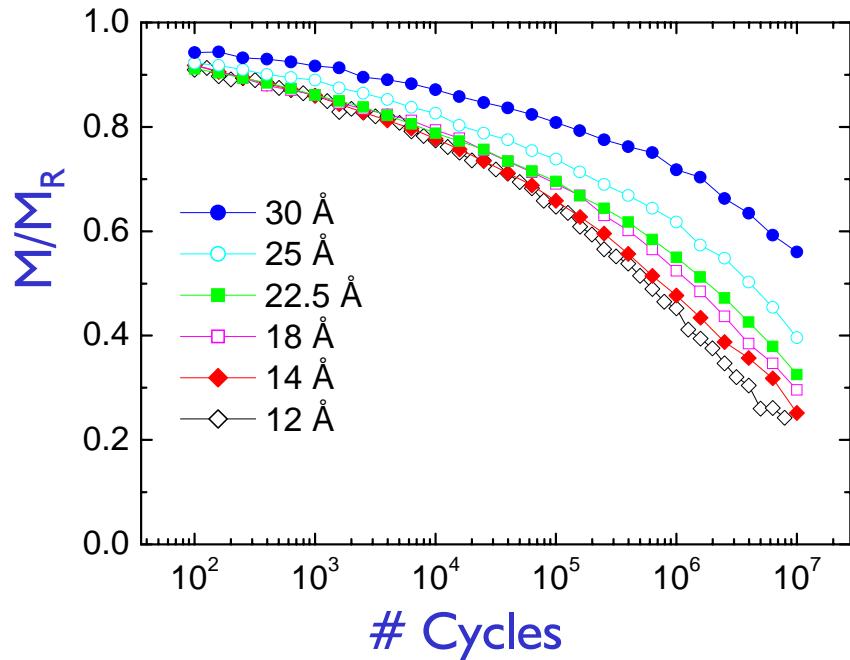
150 Å Co
 12 Å Al ox.
 20 Å Co
 100 Å Co₇₅Pt₁₂Cr₁₃



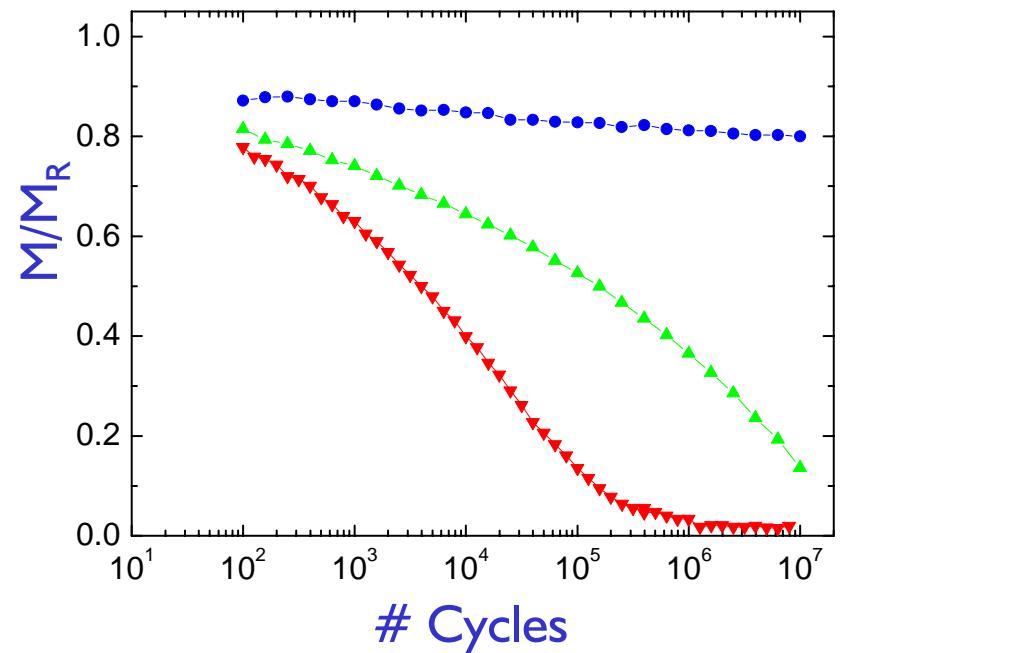
T=300 K: MTJ Set in 5 kOe: Cycled in ± 25 to ± 200 Oe

- ◆ Moment decay of hard layer caused by reversal of moment of free layer
 - ◆ No decay for fields smaller than coercive field of soft layer
 - ◆ Decay insensitive to field for field $> H_c$

Dependence of Creep on Tunnel Barrier Thickness



150 \AA Co
 $\times \text{\AA Al ox.}$
 $100 \text{ \AA Co}_{75}\text{Pt}_{12}\text{Cr}_{13}$



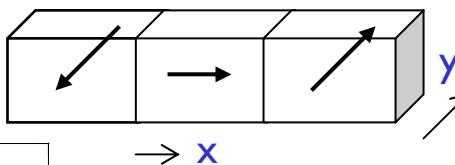
$150 \text{ \AA Ni}_{40}\text{Fe}_{60}$
 $100 \text{ \AA Co}_{75}\text{Pt}_{12}\text{Cr}_{13}$
 150 \AA Co
 $100 \text{ \AA} \& 200 \text{ \AA Co}_{75}\text{Pt}_{12}\text{Cr}_{13}$

- Creep slower with increasing tunnel barrier thickness
- Creep faster for thinner hard layer
- Creep depends on magnetic properties of soft layer

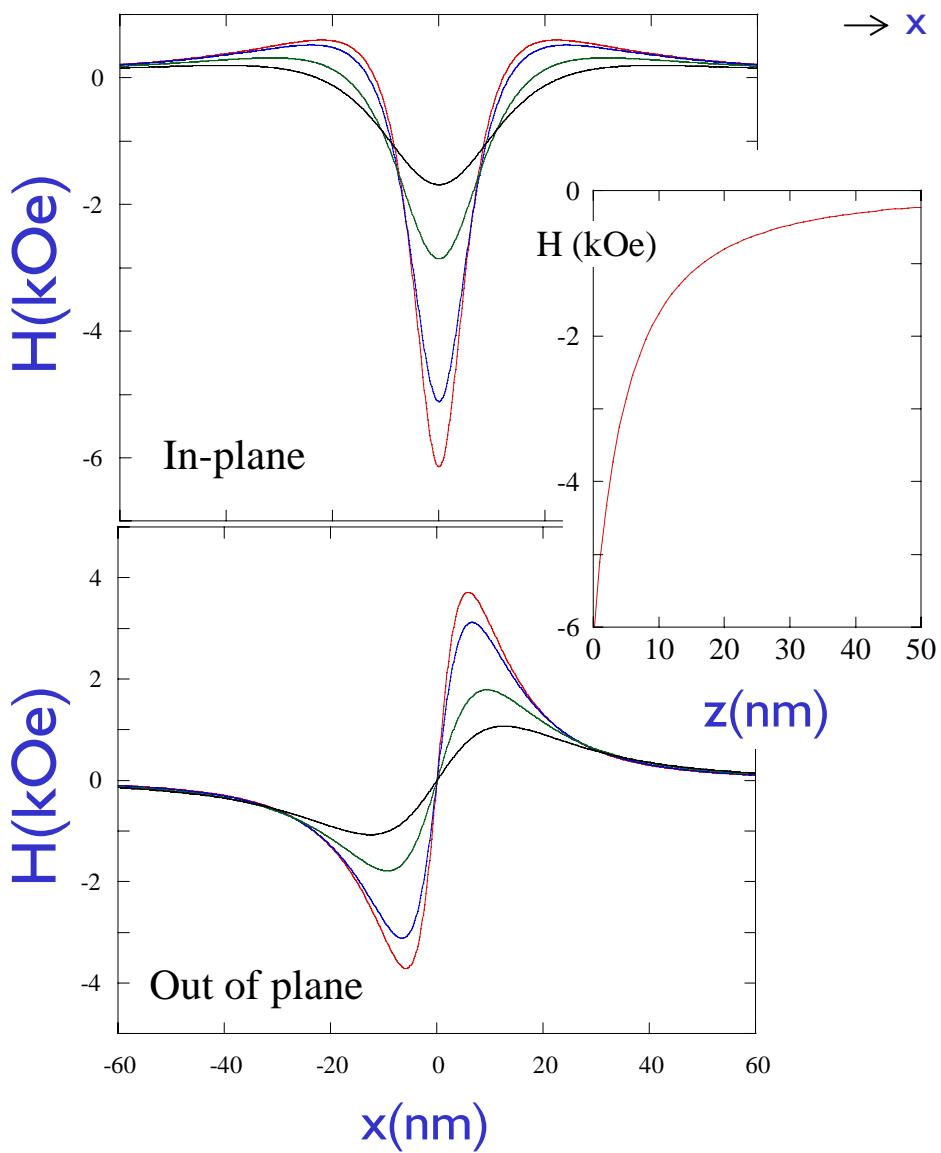
$T = 300 \text{ K}$
MTJ Set in 5 kOe
Cycled in $\pm 200 \text{ Oe}$



DW: top view

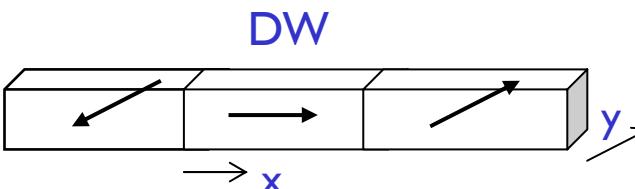
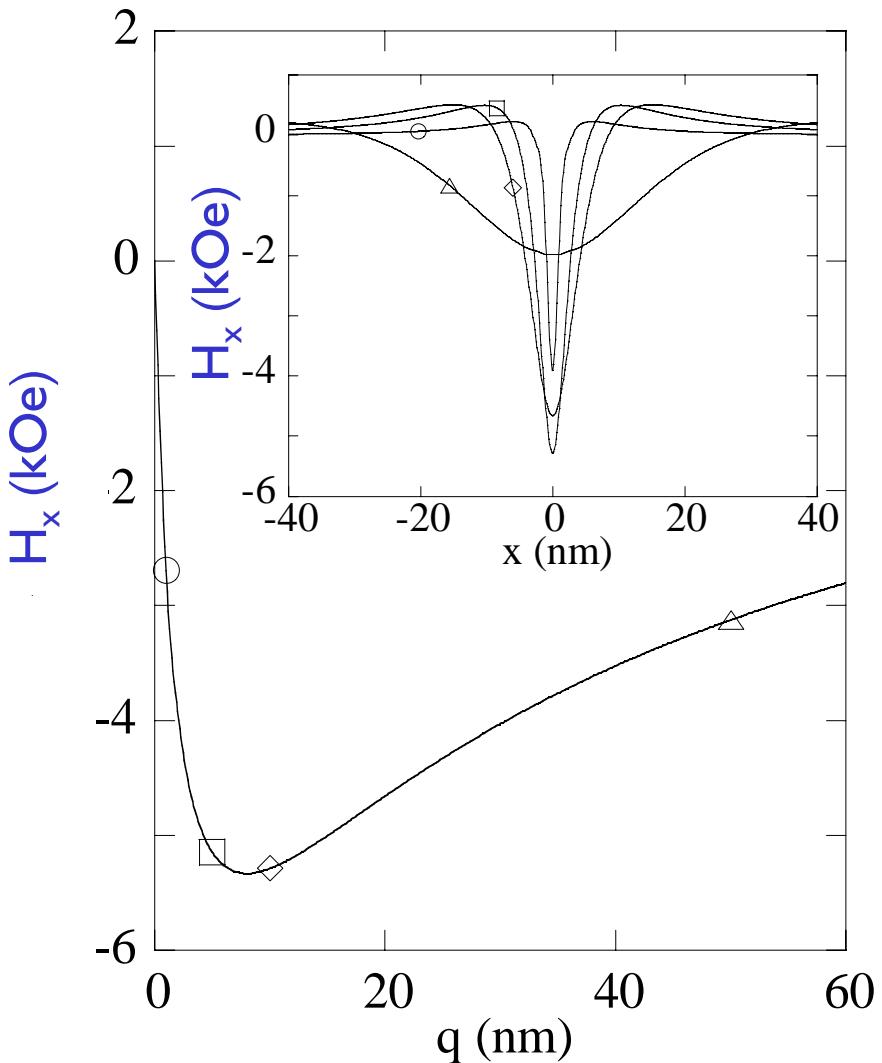


Domain Wall Stray Field Magnitude



Thomas, Samant and Parkin, PRL (2000)

Maximum Domain Wall Stray Field vs wall-width parameter, q

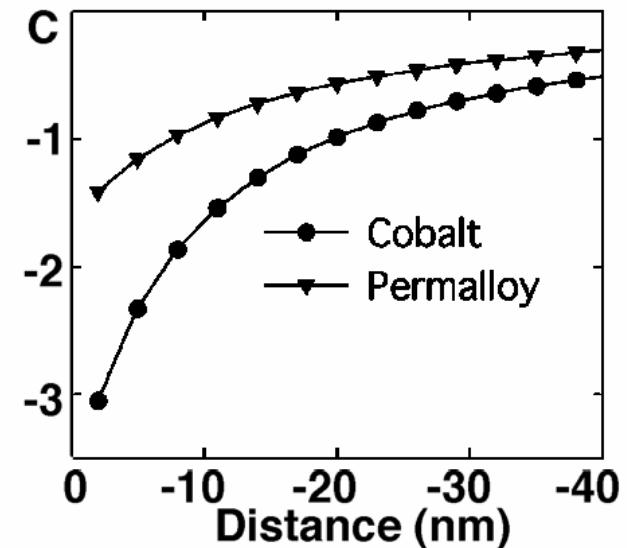
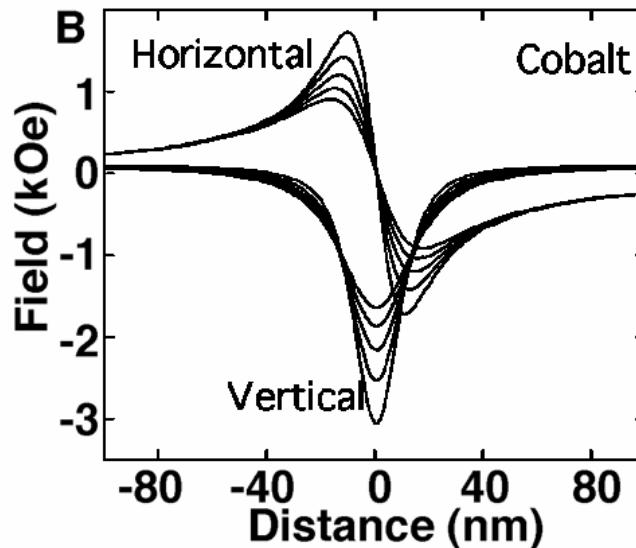
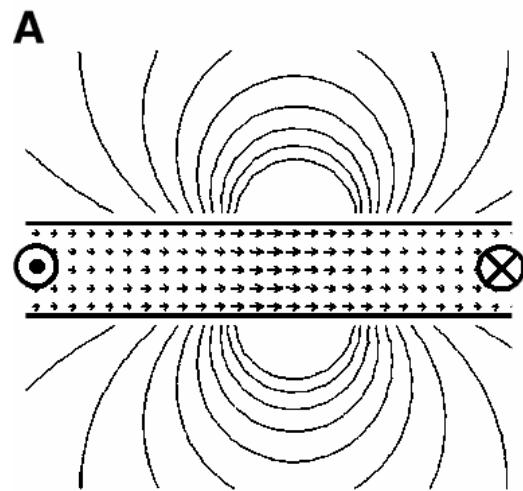


- ◆ DW stray field calculated from gradient of magnetic potential, $\Psi(\mathbf{r})$
 - ◆ For thin Co films DW likely to be of Néel type (M rotates in plane of film) and $\Psi(\mathbf{r})$ depends on $\text{div } M$ – no surface charge
 - ◆ Consider linear DW infinitely long along y (Dietze and Thomas)
 - ◆ M varies only along x ; $\Psi(\mathbf{r})$ related to M_x
 - ◆ $M_x(x)/M_s \sim q^2/(x^2+q^2)$ where q is a wall-width parameter

Thomas, Samant and Parkin, PRL (2000)

Stuart Parkin
July 7, 2003

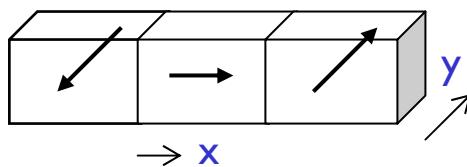
Domain Wall Fringing Fields



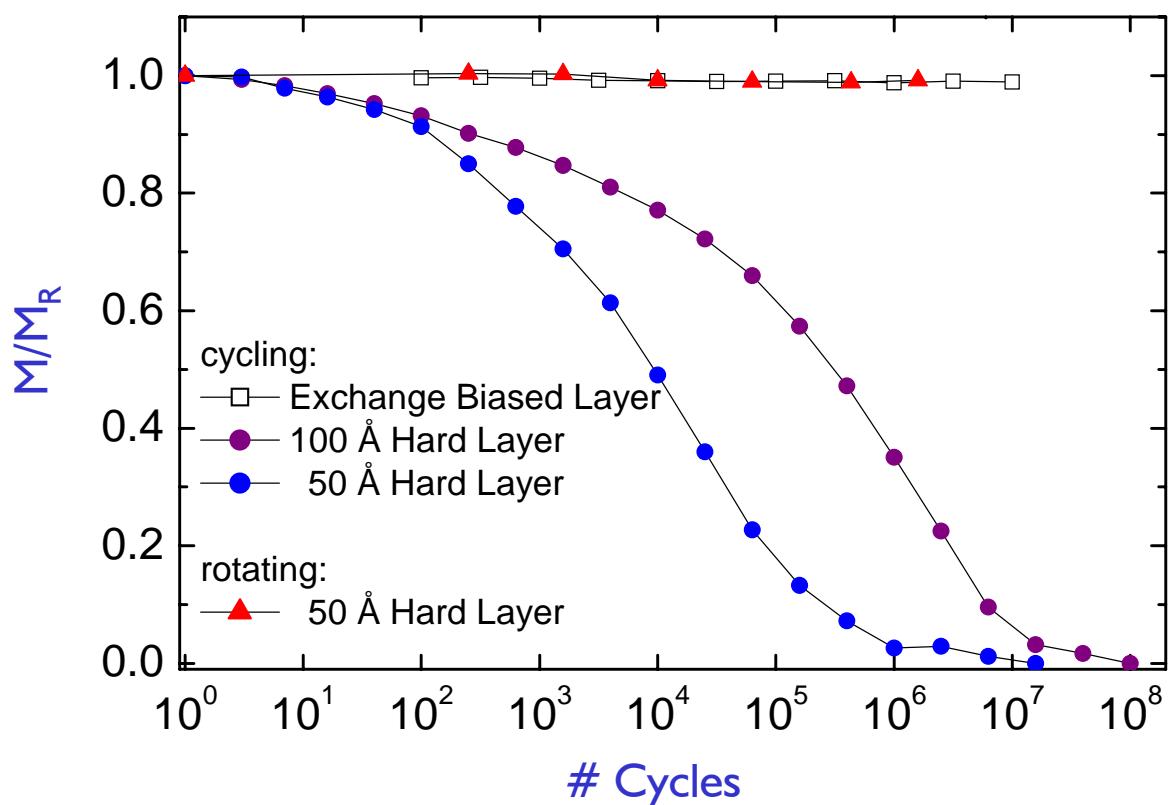
Mike Scheinefein

McCartney et al, Science (2000)

- very large stray fields from Neel wall in y and z directions



Origin of Creep in Hard/Soft MTJ



150 Å Co
 12 Å Al ox.
 20 Å Co
 100 Å Co₇₅Pt₁₂Cr₁₃

 $T = 300 \text{ K}$
 MTJ Set in 5 kOe
 Cycled in ± 200 Oe

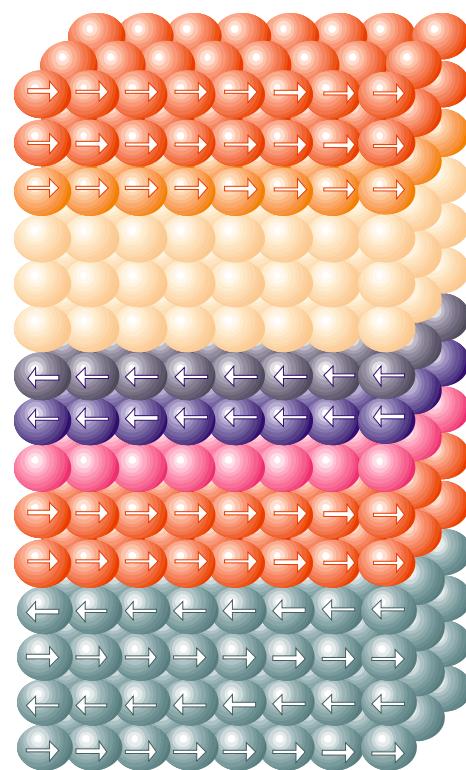
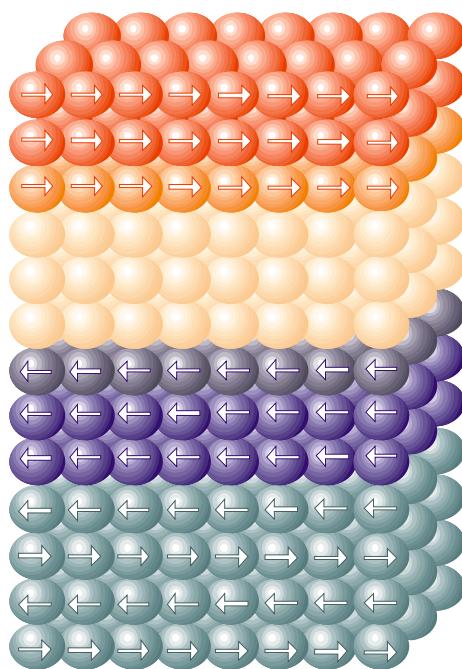
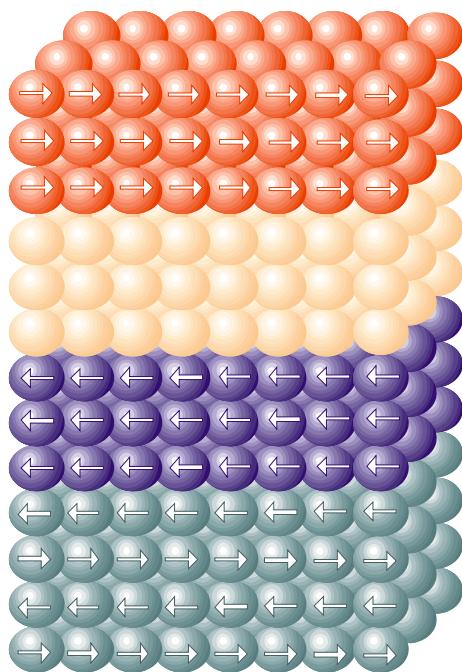
- ◆ No creep of hard layer observed when moment of free layer rotated!
- ◆ Hard layer moment in CoPtCr/Al-O/Co MTJ sandwich:
 - ◆ decays to zero after reversing moment $\sim 1,000,000$ times
 - ◆ no creep after rotating moment $\sim 1,000,000$ times
- ◆ Mechanism via motion of domain walls in free layer
 - ☺ larger charge on domain walls in Co compared to Ni₄₀Fe₆₀

Magnetic Engineering at the Atomic Scale

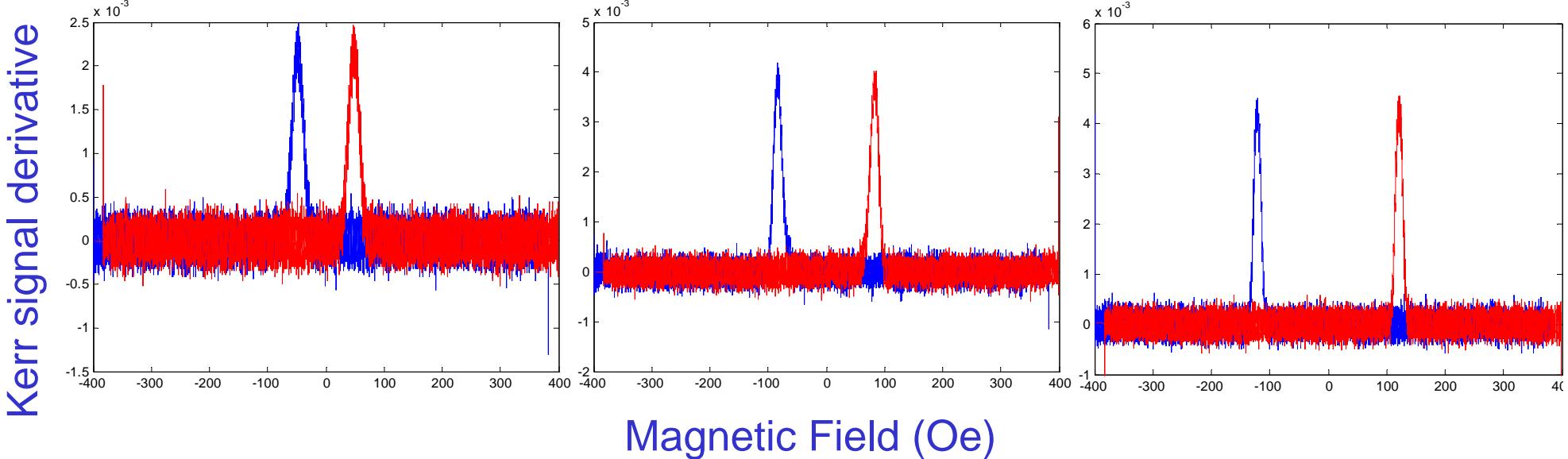
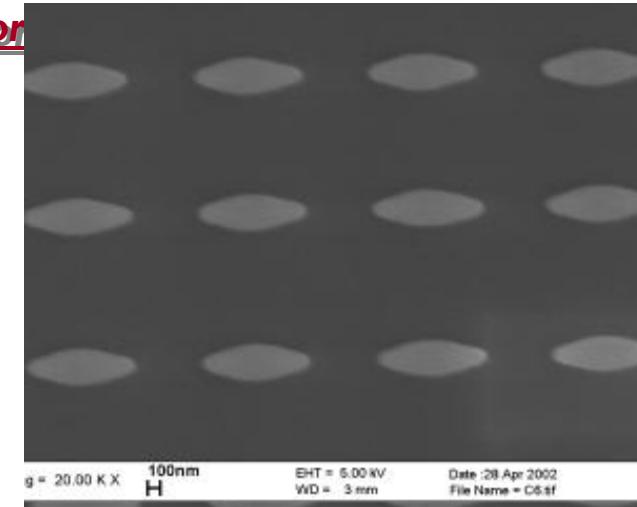
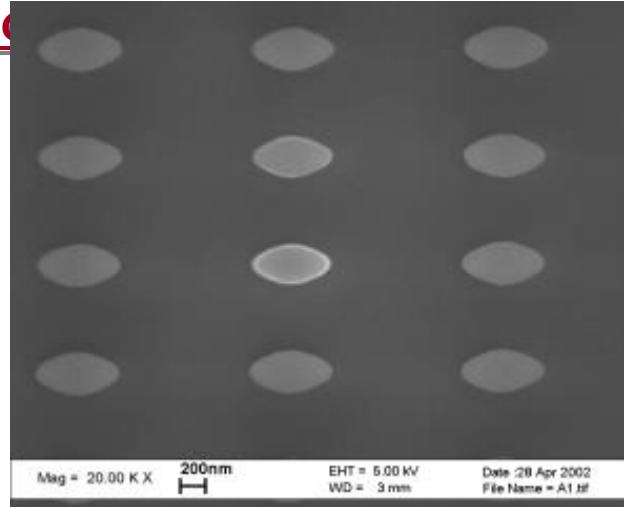
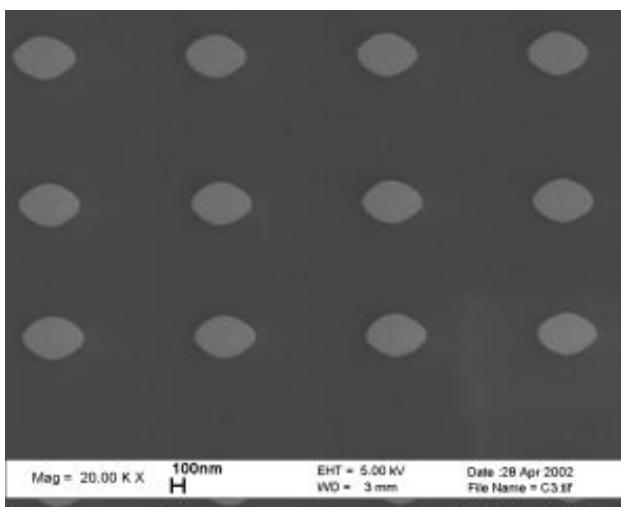
MTJ exchange biased
spin valve

+ interface
engineering

+ Artificial
Antiferromagnet

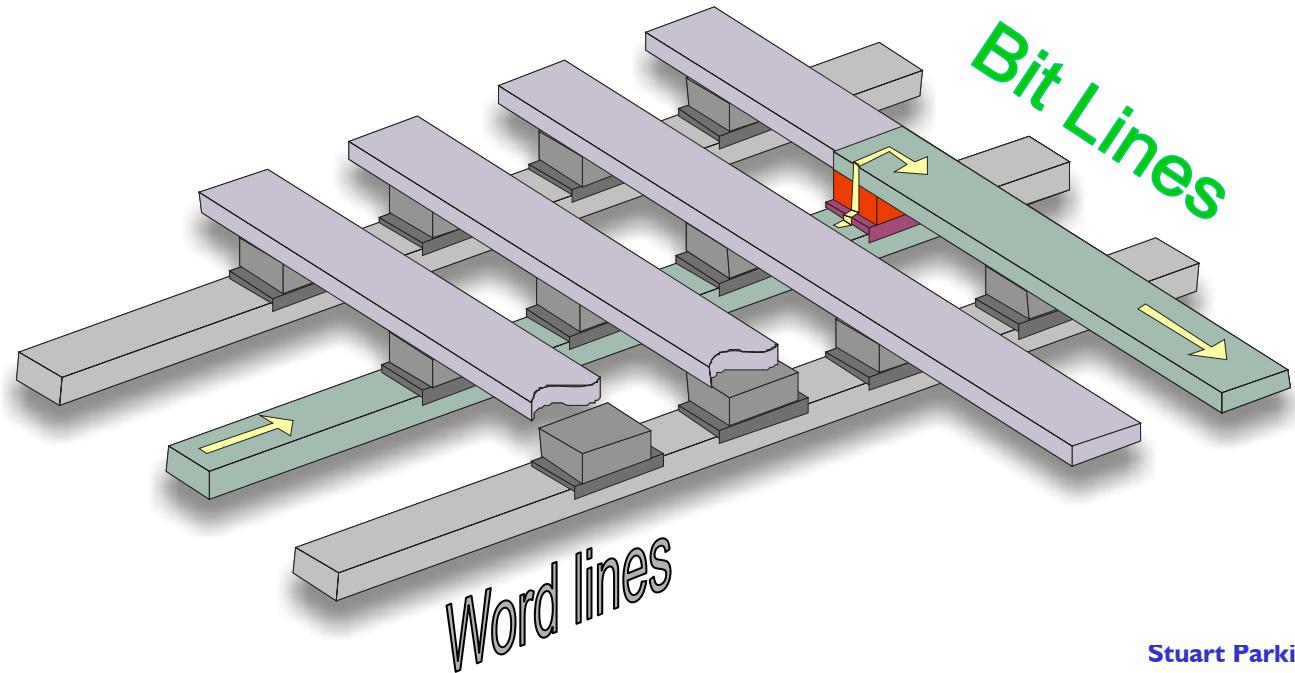


Optical Characterization of Switching Uniformity



MTJ Magnetic Random Access Memory: Reading

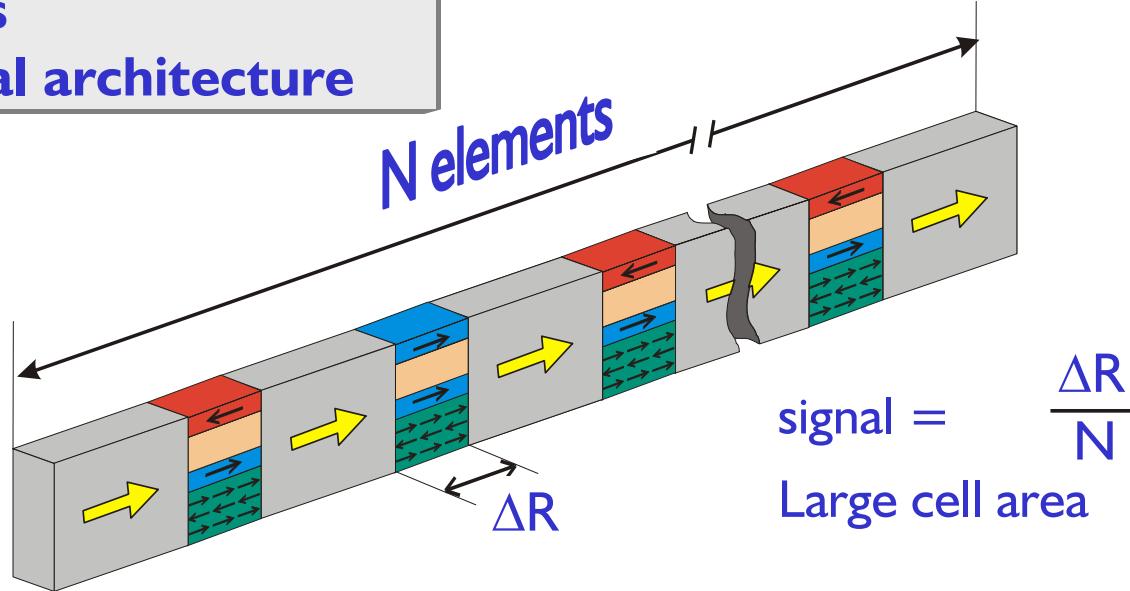
- ☺ High resistance
- ☺ High magnetoresistance (MR)
- ☺ Controllable resistance
- ☺ Weak temperature dependence
- ☺ Scalable to small sizes with high MR
- ☹ MR falls off with increasing voltage



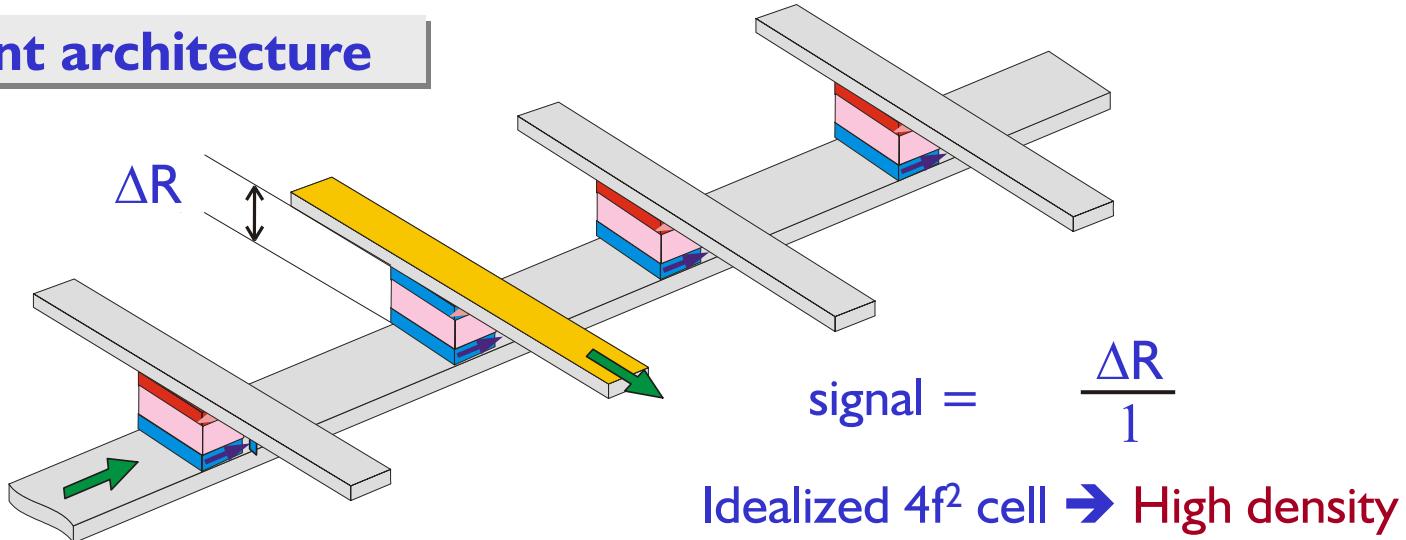
Serial vs Crosspoint Architecture

Previous MRAMs

AMR, GMR: serial architecture

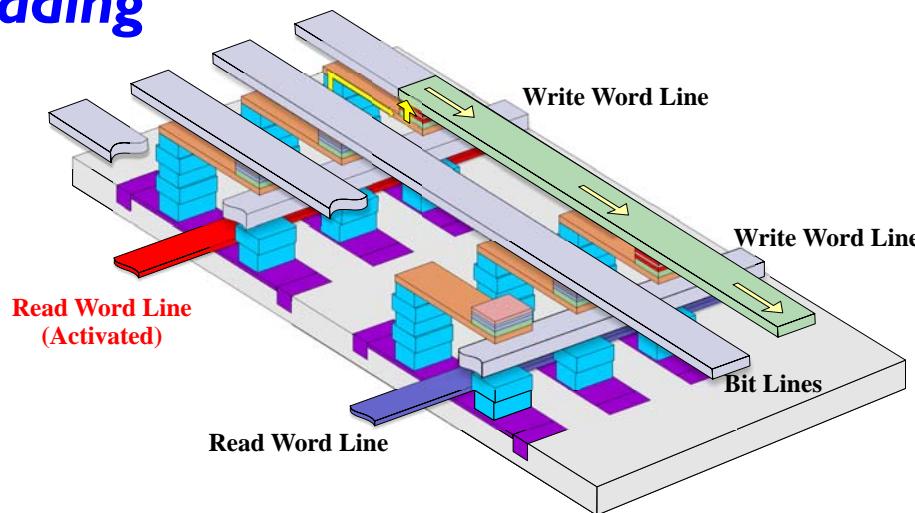


MTJ: crosspoint architecture

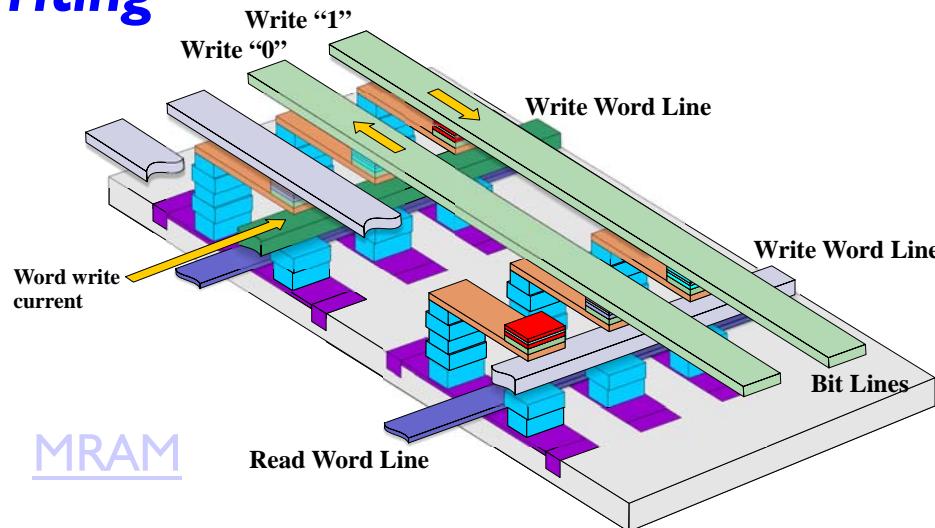


MTJ MRAM: IT-IR cell for Faster Reading

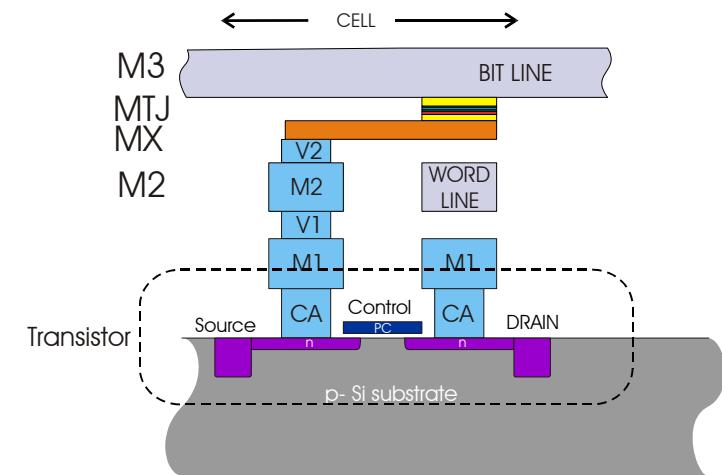
Reading



Writing

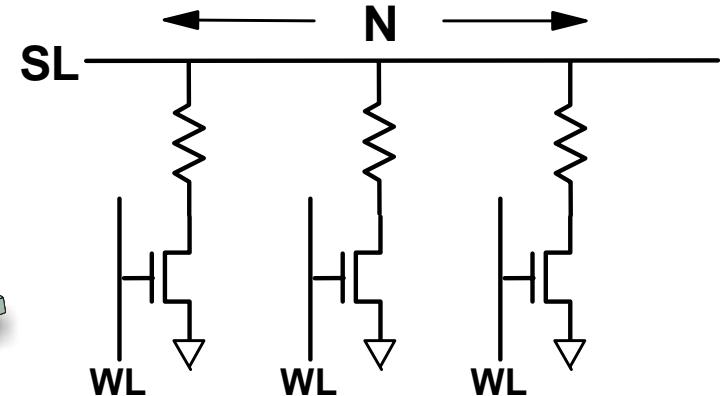
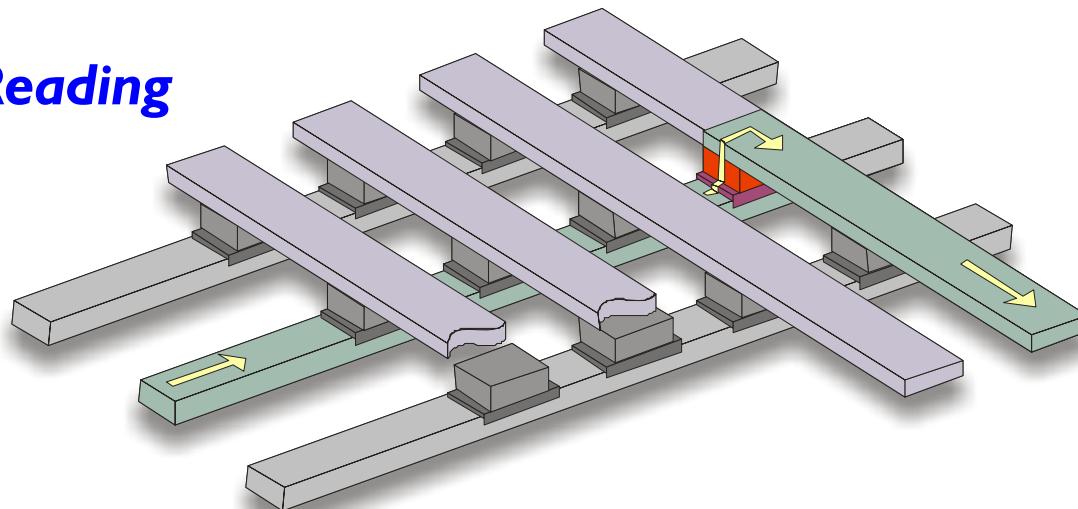


MRAM



I Transistor / I Resistor MRAM Cell

Reading



Signal \propto MR/1 → High performance

Sense power \sim 10-100 fJ: 100,000 x smaller than GMR cell!

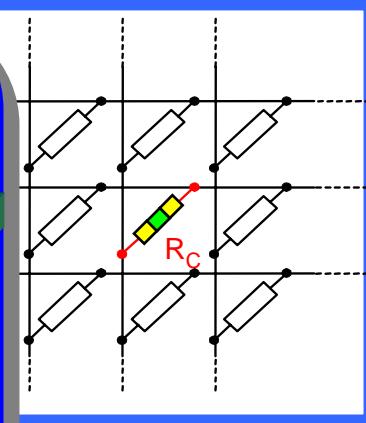
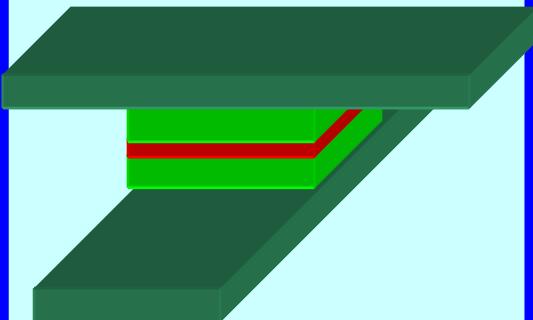
[higher MR, higher R and N \sim I]

~300 mV array voltage → Low power

IT/IR increases size of cell

MRAM Cell Concepts

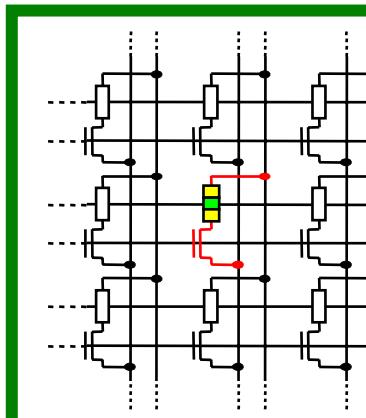
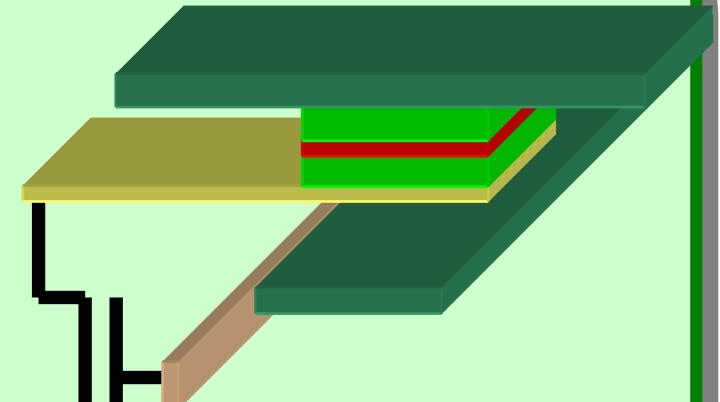
Cross point cell (ITJ)



- ◆ Small cell area ($>4F^2/N$)
- ◆ Slower random access time ⁽¹⁾
- ◆ Flash like

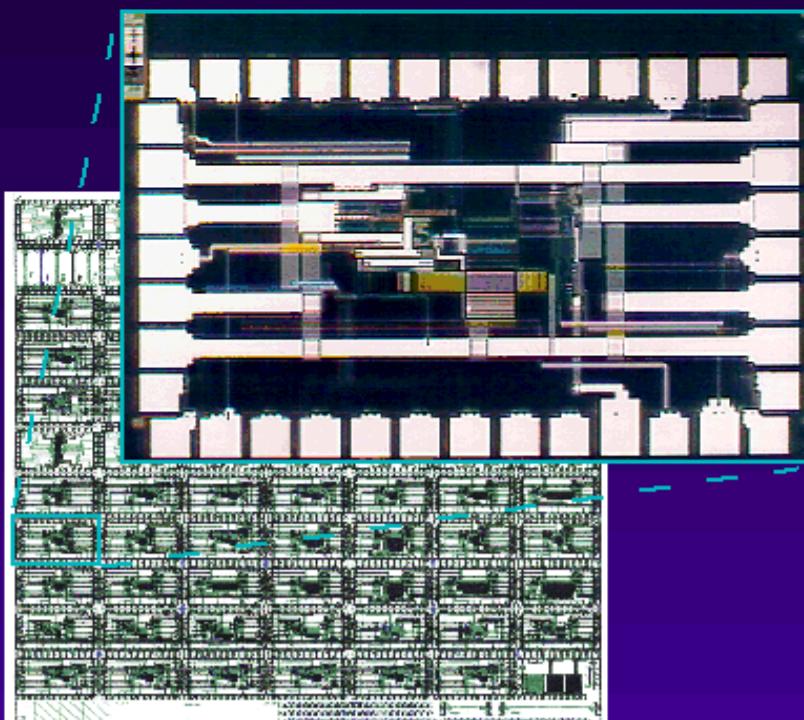
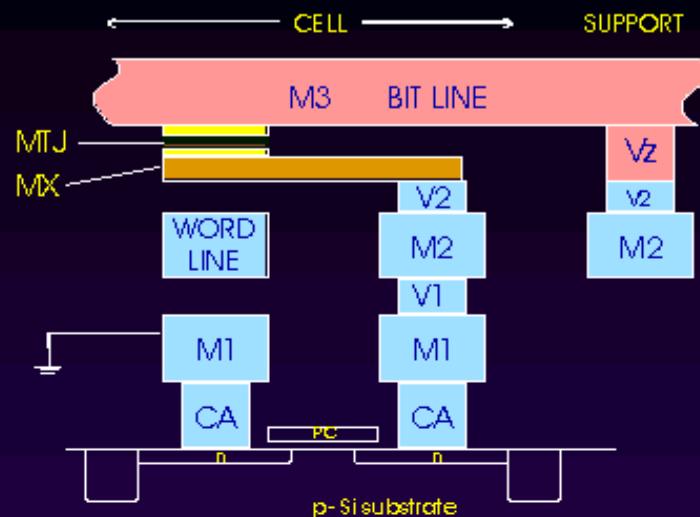
⁽¹⁾ Dependent on array size

FET cell (ITJ-IT)



- ◆ Larger cell area ($>8 F^2$)
- ◆ Faster random access time
- ◆ SRAM like ($\leq 10\text{ns}$)

MTJ MRAM Demonstration



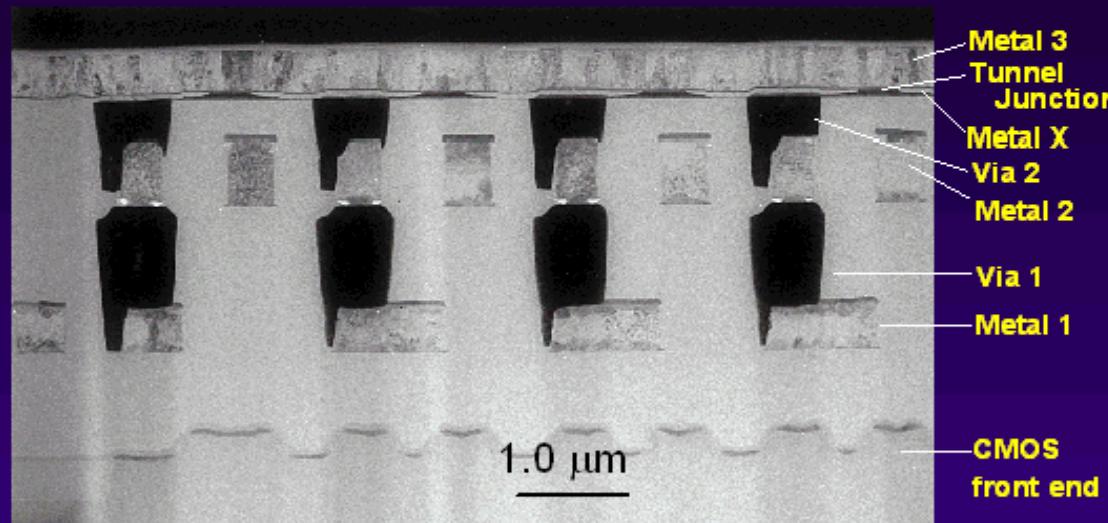
MTJ MRAM

As fast as SRAM, As dense as DRAM and
Non-volatile - no power needed to maintain memory

MRAM1 Characteristics

- 77 chiplets, 1 mm x 1.6 mm, 1K bit to 4K bit arrays
- Access time achieved: 2.25 ns
- Write time demonstrated: 2.3 ns
- Cycle time exercised: 10 ns (tester limited)

Via/ROM Cell 1 Cell 2 Cell 3



MRAM1 Processing

- CMOS 6SF fabricated in BTV on 200 mm Si, 3 special steps
- Wafers diced into 1" squares
- MTJ and MX materials (8 layers) deposited in Almaden
- MX, TJ, Vz, and M3 processed in Yorktown with e-beam lith

The MRAM Development Alliance

Formation: November 2000, IBM + Infineon

Mission:

Design and develop jointly a competitive
and scalable MRAM technology.



- 200mm MRAM technology development
- Cu BEOL technology
- Two architectures
 - FET for high performance
 - Cross point for high density

The MRAM Development Alliance

Project Locations



Yorktown Heights, NY



East Fishkill, NY
(main development site)



Almaden, CA



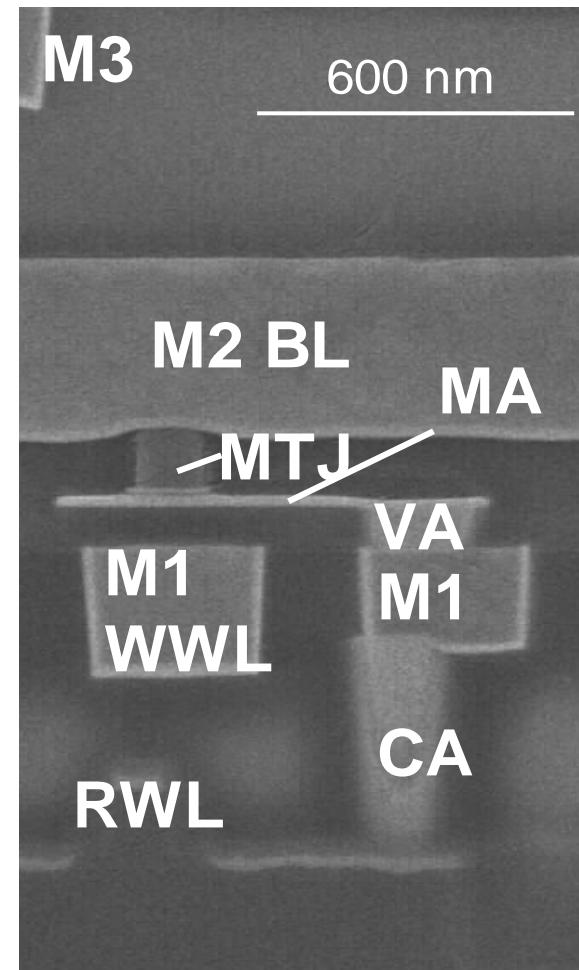
Burlington, VT



Erlangen

Process Integration in 0.18 μ m Technology

Process Flow
Final Cu Level (M3)
2nd Cu Level (Bitline M2)
ILD, Planarization
Local Interconnect (MA)
MTJ Encapsulation
MTJ RIE Patterning
MTJ Stack Deposition
Contact Via (VA)
M1/VA ILD Deposition
1st Cu Level (Write Line M1)
0.18um CMOS fabrication

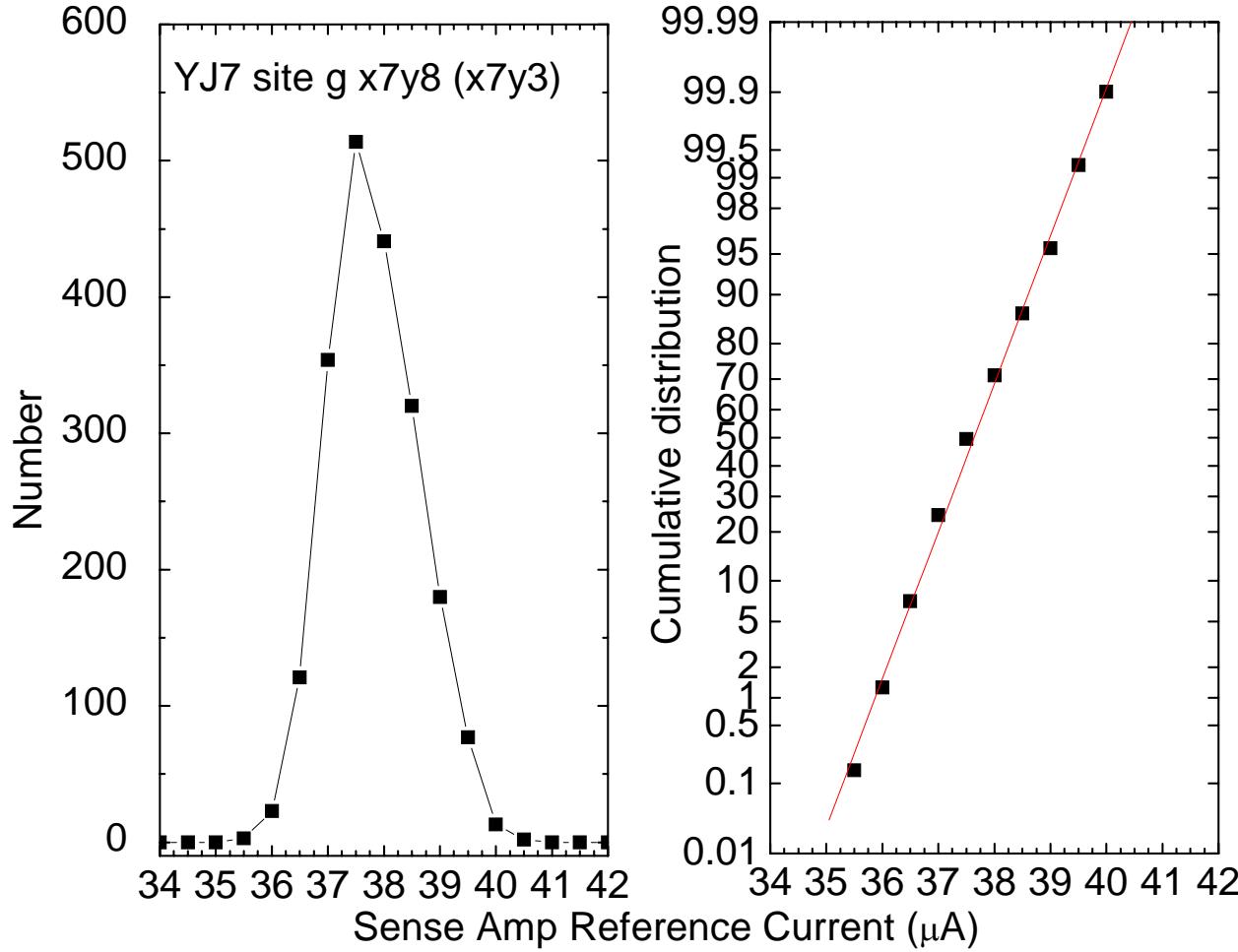


Key integration processes are:

- MTJ patterning by RIE
- Post etch treatment of the MTJ
- Encapsulation of the MTJ with a suitable low temperature ILD.

MTJ Control for Read Yield

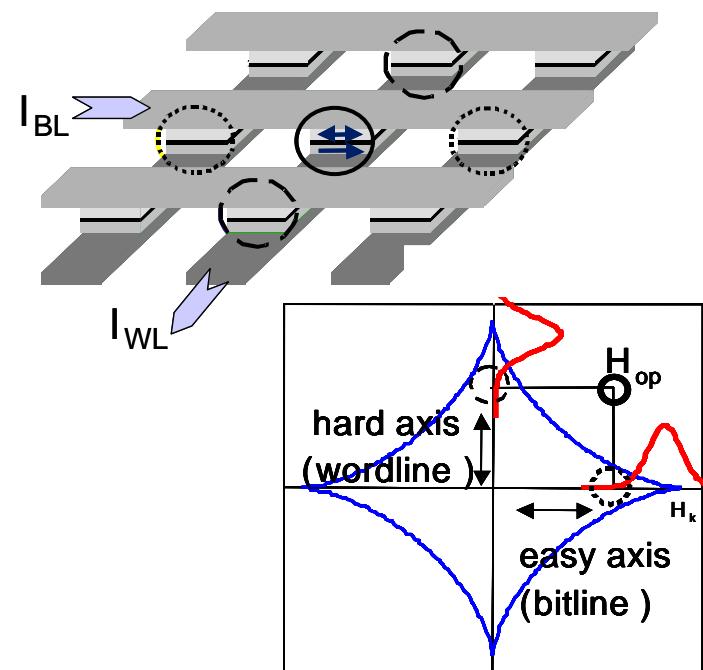
Resistance distributions within a functional 2kbit array



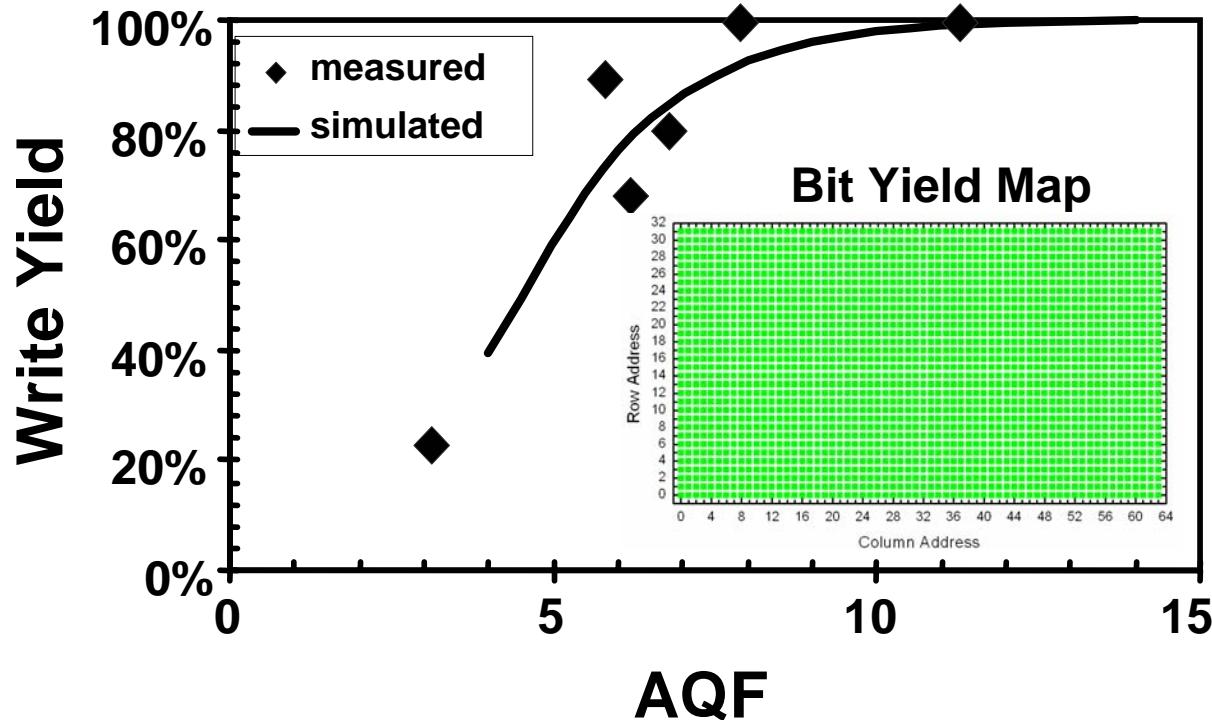
- 0.2x0.7 μ m² MTJs
- Gaussian distribution
 - $\sigma_R \sim 2\%$
- No outliers

MTJ Control for Write Yield

Test Results Compared to Simulations

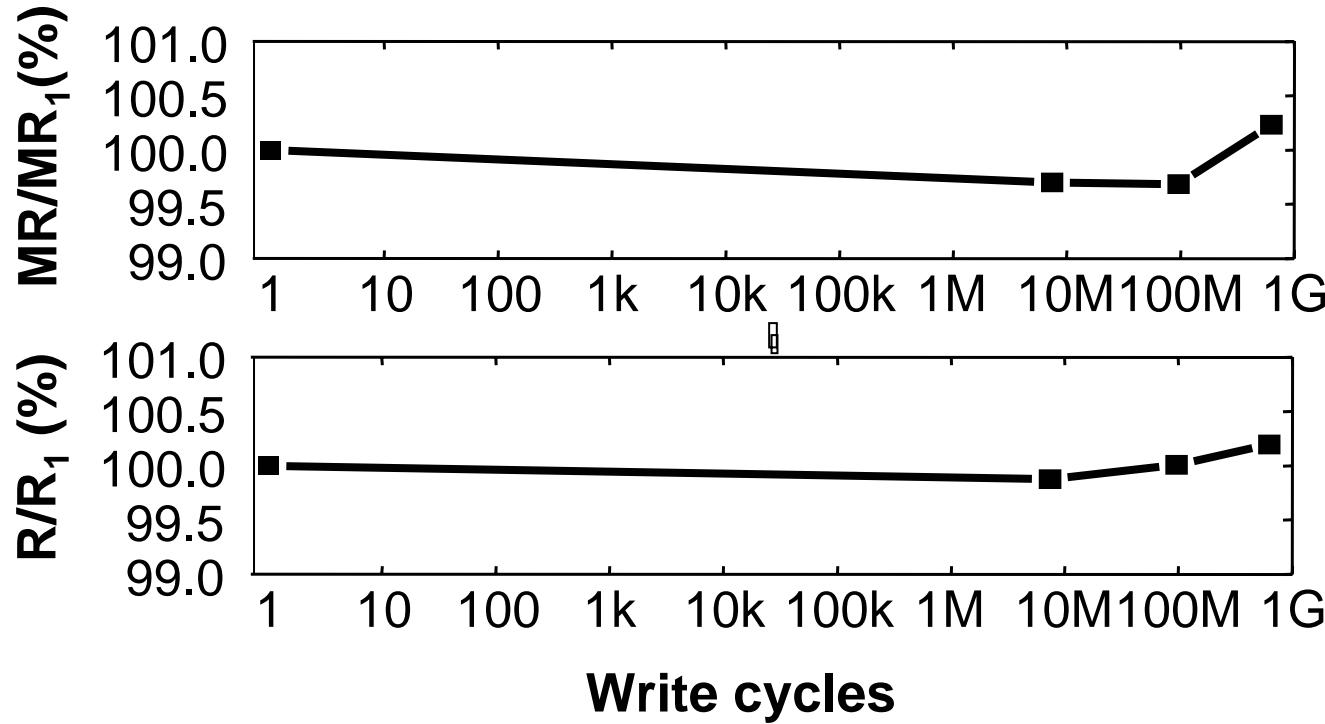


Array Quality Factor:
 $AQF = H_{sw}/\sigma_{Hsw}$



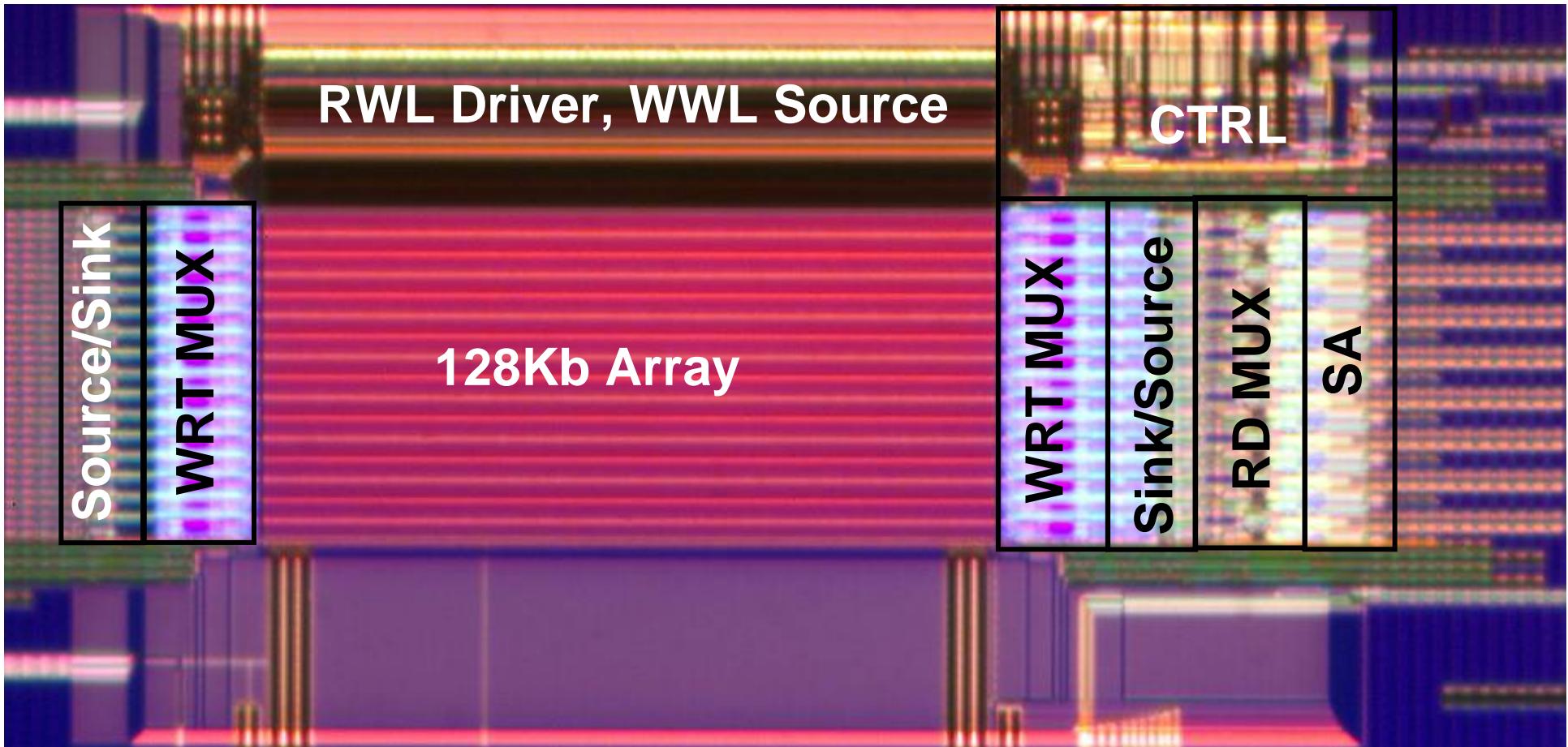
Write yield dependence on AQF:
Test results compared to simulations
(Inset shows checkerboard yield map for 2kbit array)

Endurance



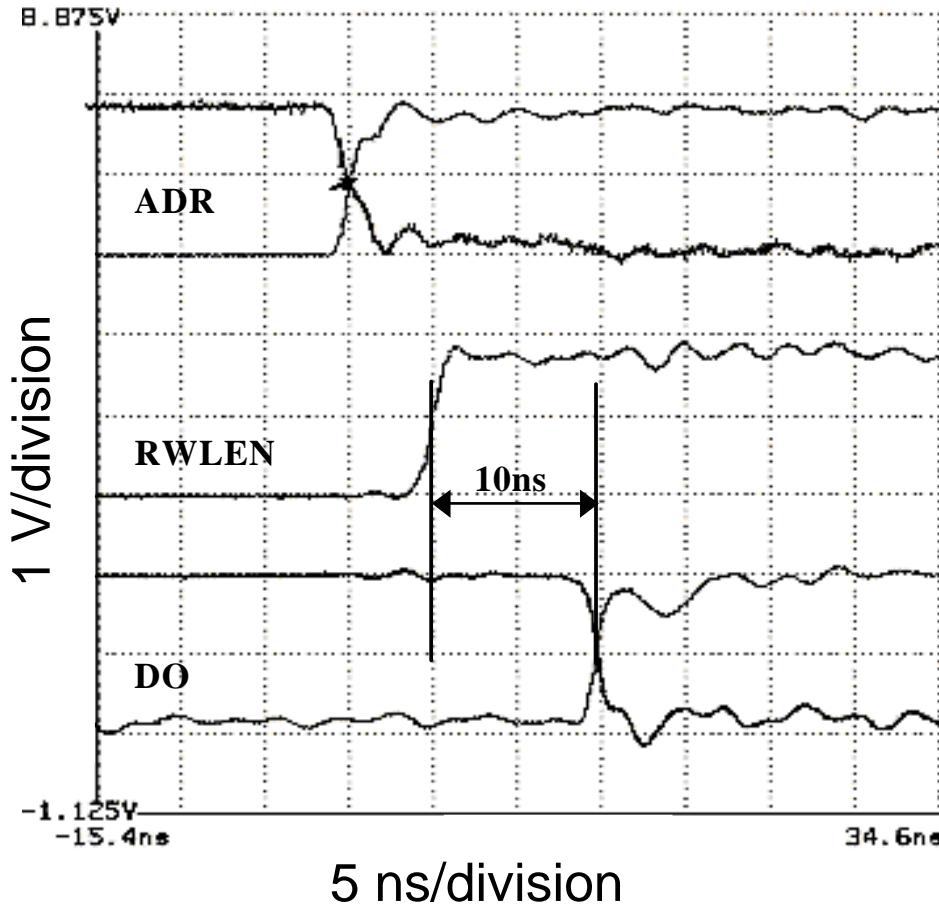
- Blanket write cycles on a 2kb array
- No significant degradation of median MR and MTJ resistance through 630 million cycles

128 kbit MTJ MRAM Core Array Fabricated in a 0.18 μm Cu Technology



Cell pitch = 1.1 μm (WL) x 1.27 μm (BL)
→ Cell area 1.4 μm^2

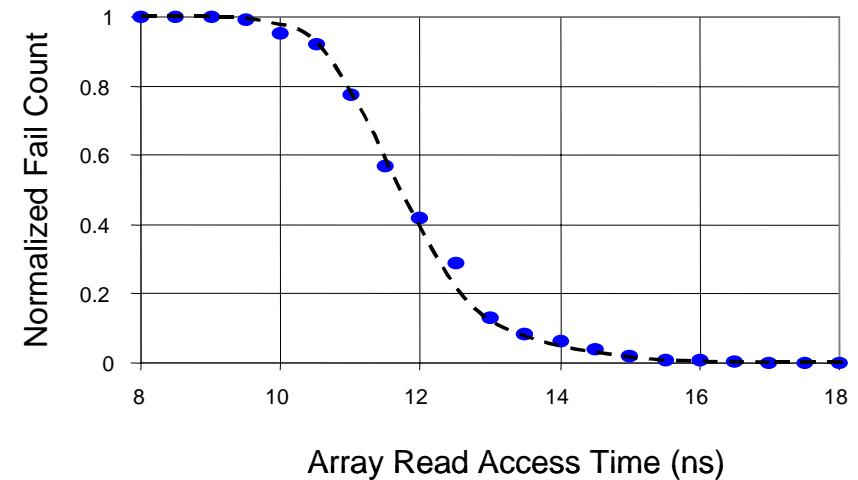
FET Cell Read Performance



Array read access time measurement at 1.8V

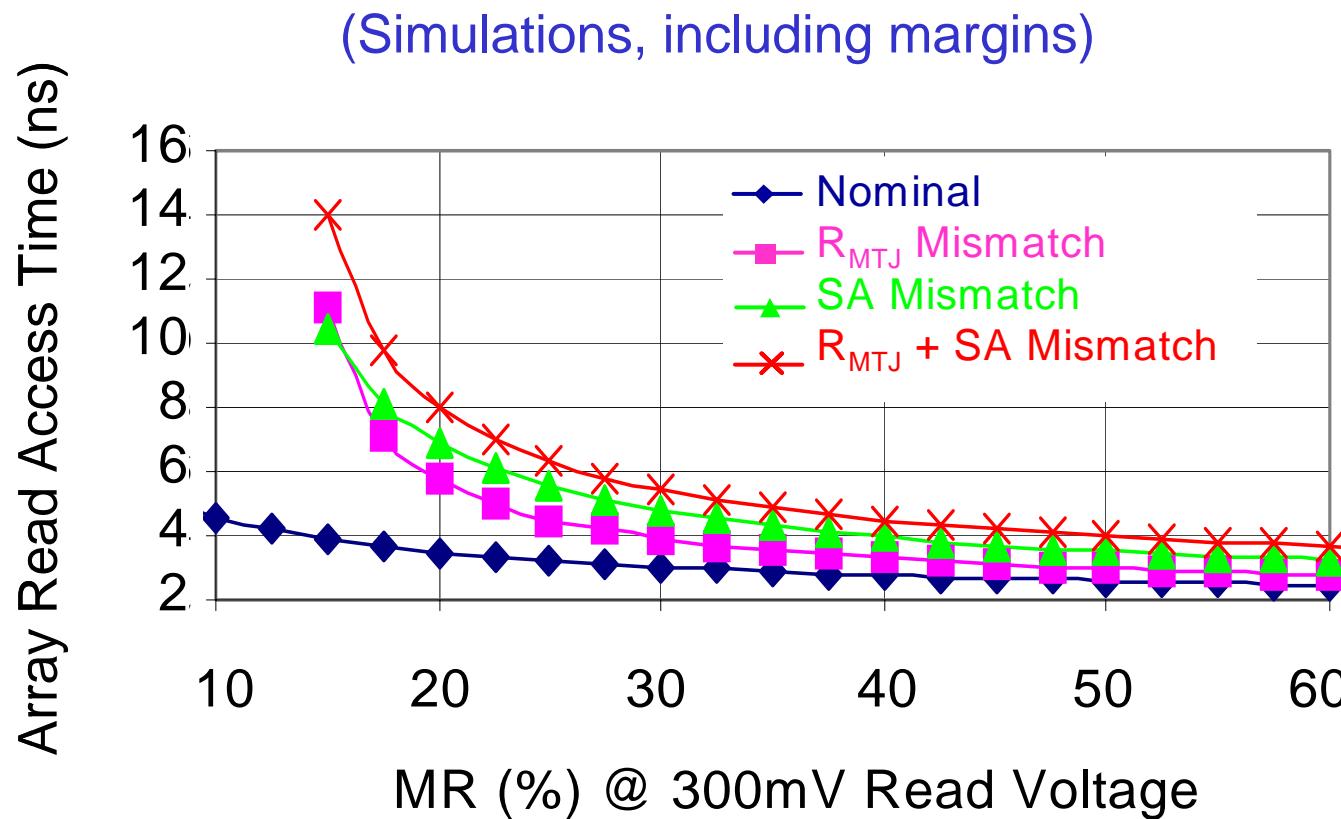


128 kbit FET MRAM test chip



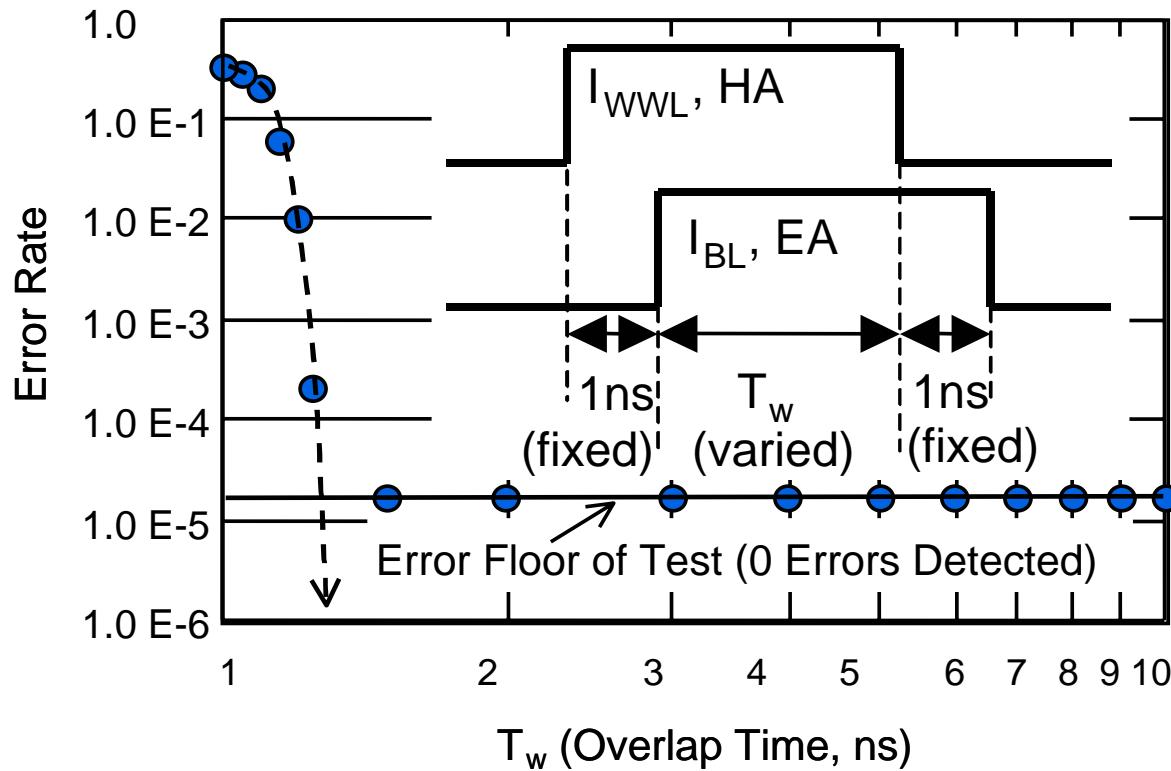
Measured distribution of access times

Performance Analysis of FET MRAM Read Operation



- Through optimization of the MTJ resistance ($R_L = 5 \text{ k}\Omega$), optimization of the SA device matching and improvements in MR, a yieldable array read access time of 5ns is achievable with MR = 35% @ 300mV MTJ bias voltage.

Time Required For Cell Writing



→ No errors observed beyond 1.5 ns T_w

Comparison of Memory Technologies

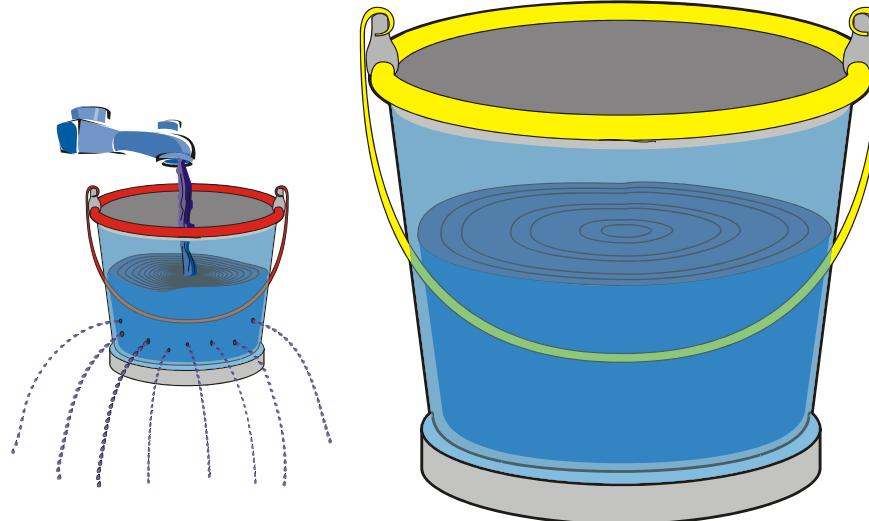
Existing Products

Technology Potential

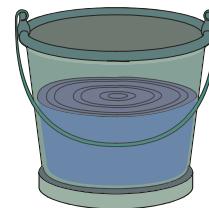
	SRAM	DRAM	NAND Flash	NOR Flash	IT-IMTJ MRAM	XPC MRAM
Cell size in F ²	100	8	5	6	>8 [published: 20-40]	>4
Supply Voltage	2.5 V	2.5 V	1.8 V	3.3 V	1.8 V [published: 2.5-3.3V]	1.8 V
Retention Power	1μW-375 mW	10 mW	0	0	0	0
Retention Time	∞ [with power]	64 ms	10 yrs	10 yrs	10 yrs	10 yrs
Random Read Access	2-100 ns	60 ns	10 μs	90 ns	10ns-50ns [published: 3ns–50ns]	50ns-1μs
Random Write Access	2-100 ns	60 ns	100 μs [erase 100 ms]	10 μs [erase 100 ms]	10-40 ns [published 3ns-50ns]	20-40 ns
Endurance	>10 ¹⁵	>10 ¹⁵	>10 ¹⁵ read 10 ⁵ write	>10 ¹⁵ read 10 ⁵ write	10 ¹⁵ [expected]	10 ¹⁵ [expected]

Magnetic Random Access Memory (MRAM)- The Perfect Memory!

**DRAM is like a
leaky bucket:
Must be
constantly
refreshed
to maintain
contents**



**The SRAM
bucket
doesn't leak,
but is a much
bigger bucket**



**MRAM is a
small bucket
that does not
need constant
refilling**